

Persistent Sputtering Yield Reduction in Plasma-Infused Materials

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International Online Plasma Seminar (IOPS)

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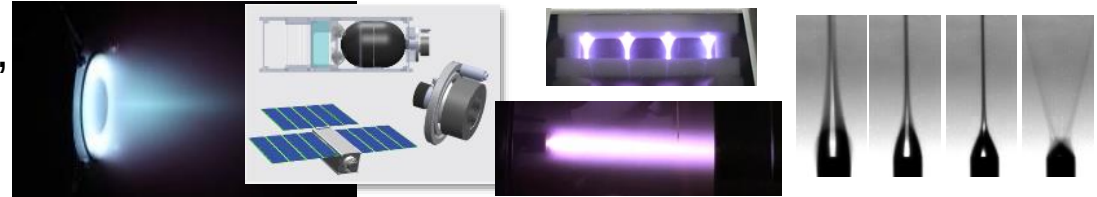
UCLA

PLASMA & SPACE PROPULSION
LABORATORY

UCLA Plasma & Space Propulsion Laboratory

Plasma Technology

Electric Propulsion,
Plasma Devices,
Cathodes, Fusion

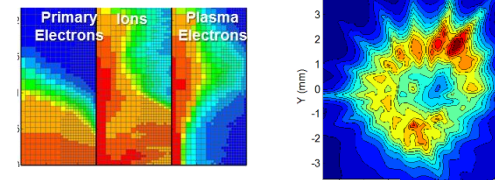


Plasma-Material
Interactions (PMI)

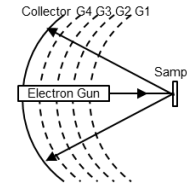


Applied Plasma Science

Plasma
Control/Confinement

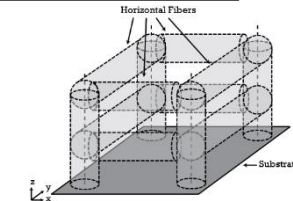
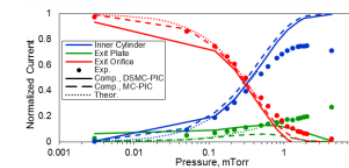


i-SEE/e-SEE
i-n
e-transport



Plasma Physics

Canonical Experiments for
Plasma Model Validation

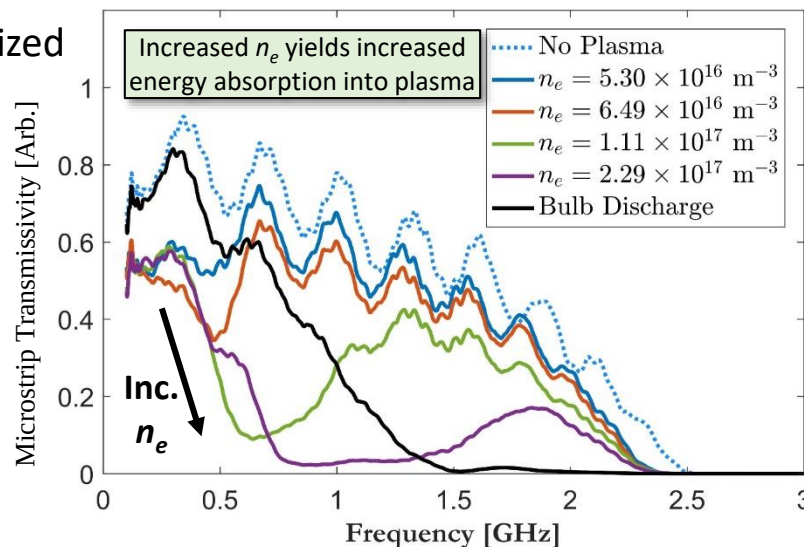
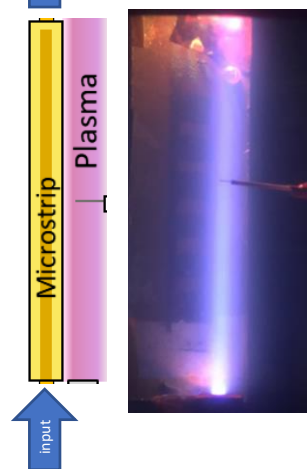


Major Accomplishment:

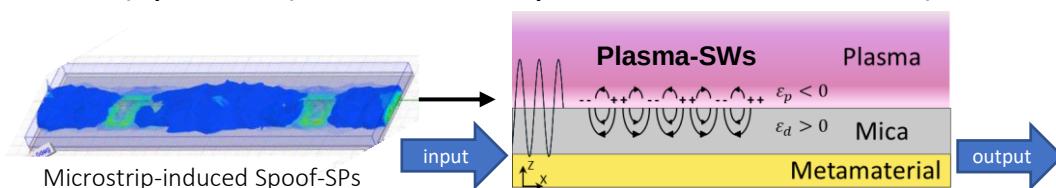
Demonstrated **plasma-functionalized metamaterials** via surface wave interactions (shown on this slide)

Discovery:

Plasma-functionalized metamaterial



Understanding: Energy absorption caused by spoof surface plasmon (Spoof-SP) excitation of plasma surface waves (Plasma-SW)

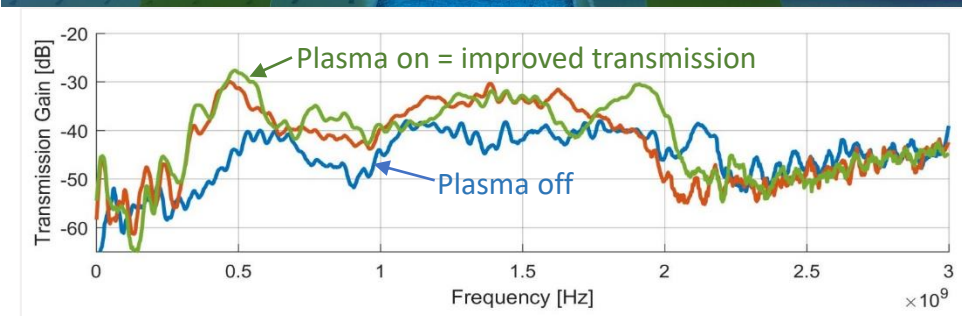
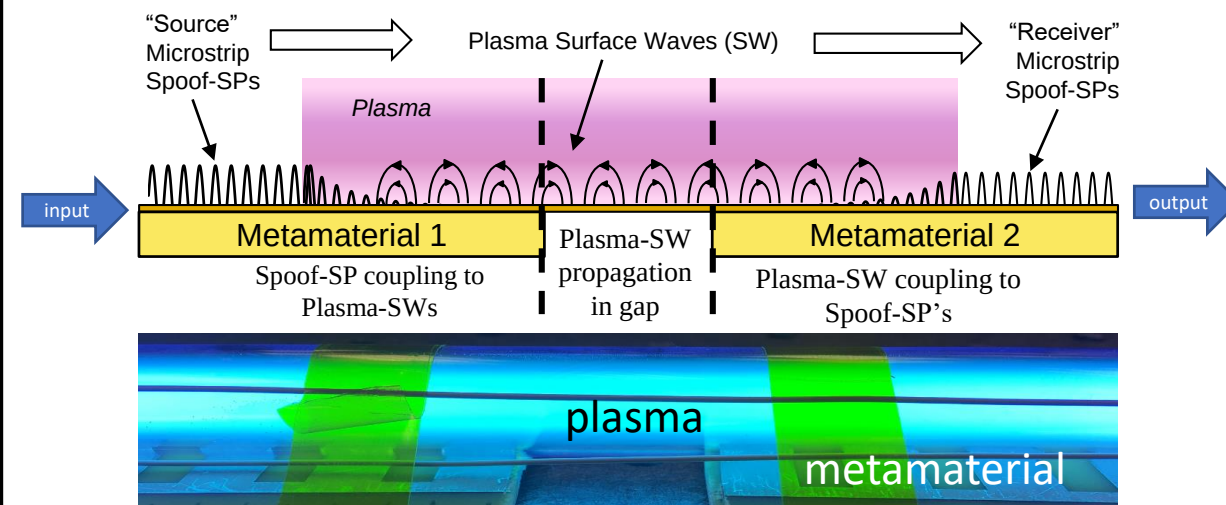


Future Applications and Research:

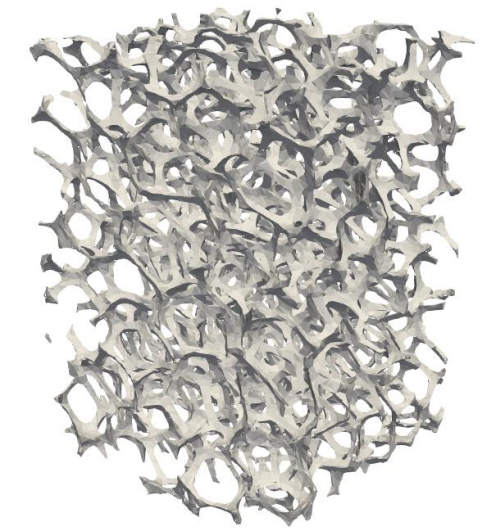
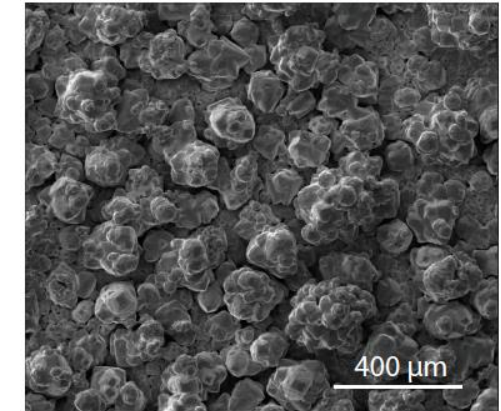
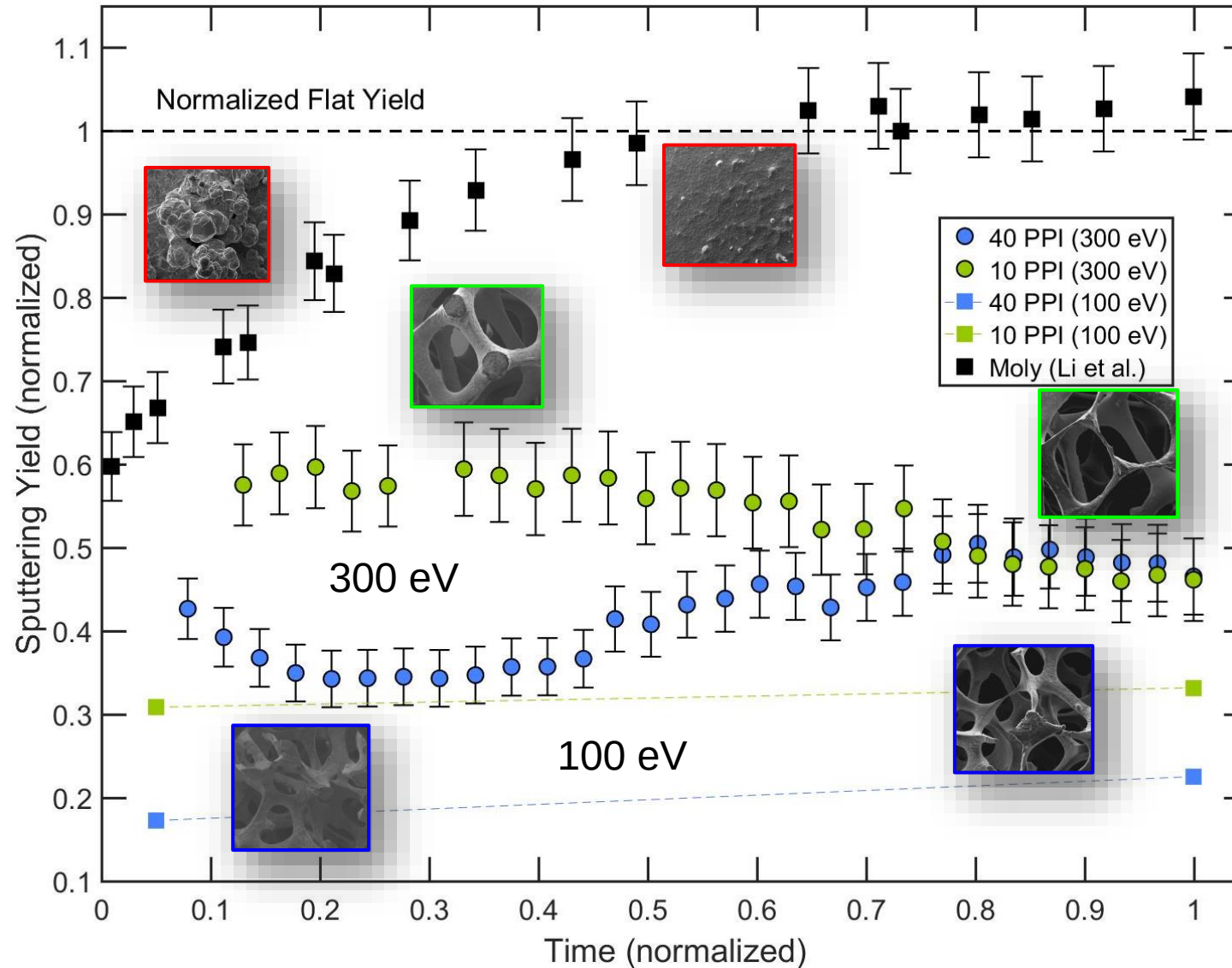
1. Active protection for sensitive electronics
2. Plasma-tunable bandpass switching and protection

Implementation: Tunable plasma bandpass switch

Uses “reciprocal-coupling” of Spoof-SP → Plasma-SW → Spoof-SP



Sputtering Yield for Complex Surfaces and Materials



Li G., Wirz R.E., "Persistent Sputtering Yield Reduction in Plasma-Infused Foams," *Physical Review Letters*, 126 (3), 035001 (2021) <https://doi.org/10.1103/PhysRevLett.126.035001>

PMI Lab Members/Contributors



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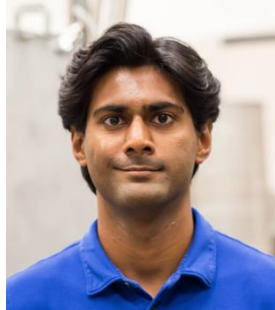
Dr. Gary Li



Dr. Taylor
Matlock



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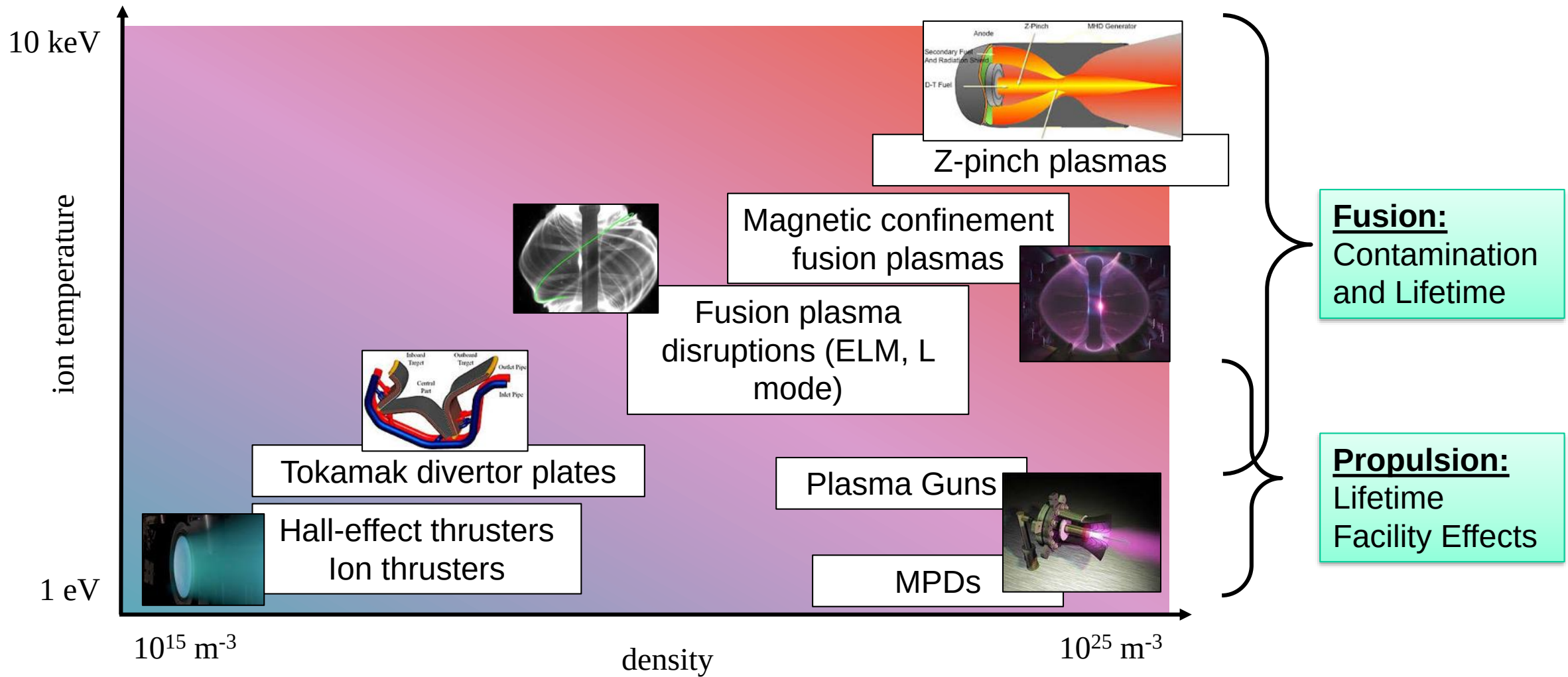
Angelica
Ottaviano



Nolan
Uchizono

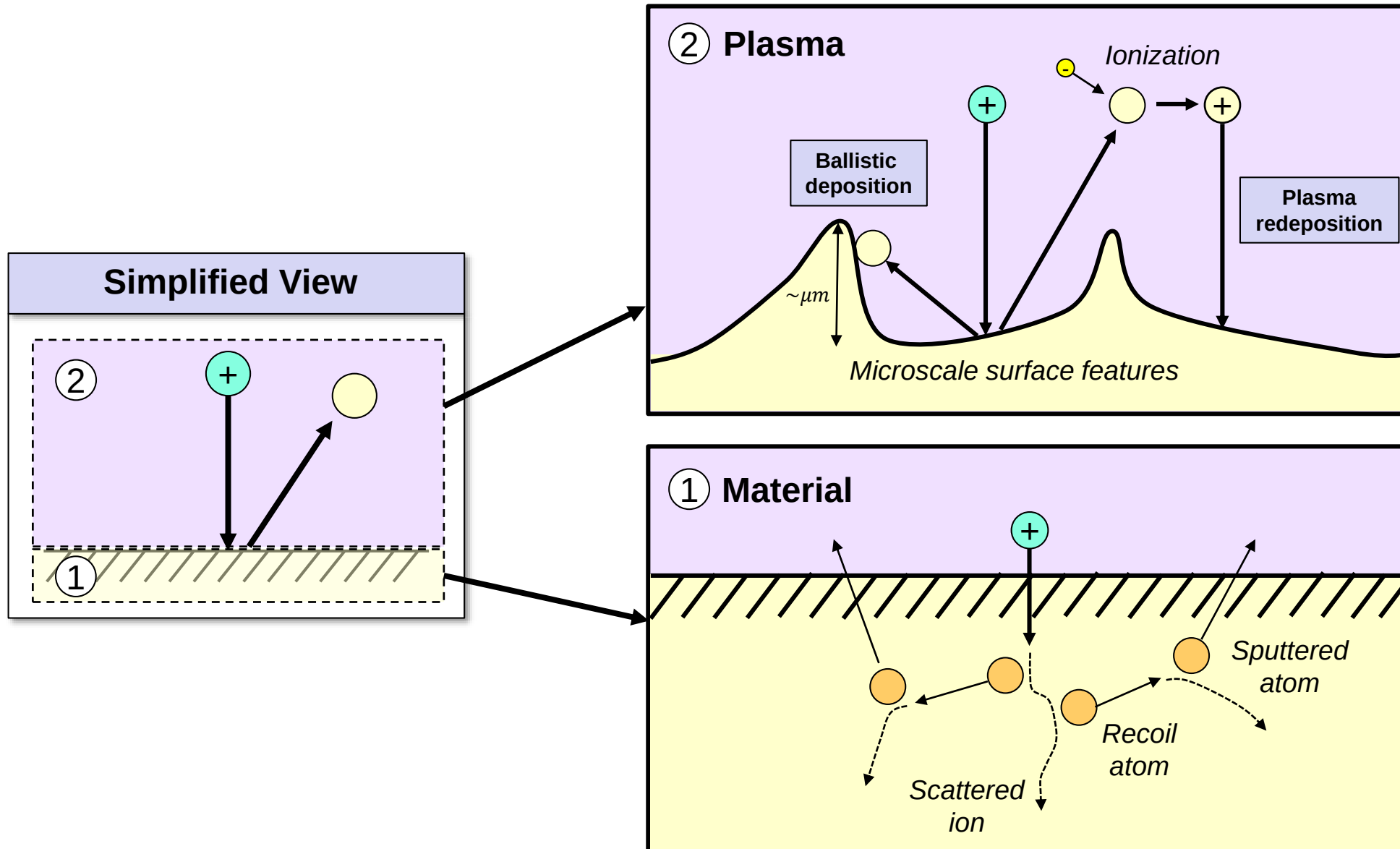
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Fusion and Electric Propulsion (EP) PMI regimes

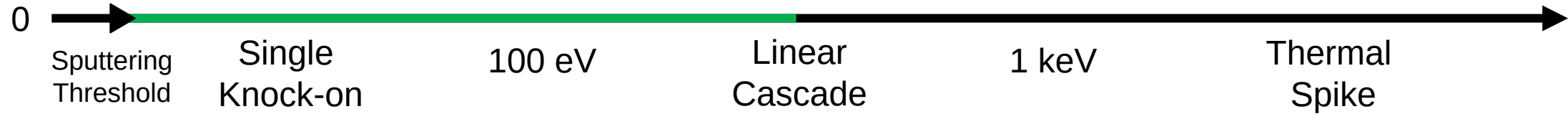
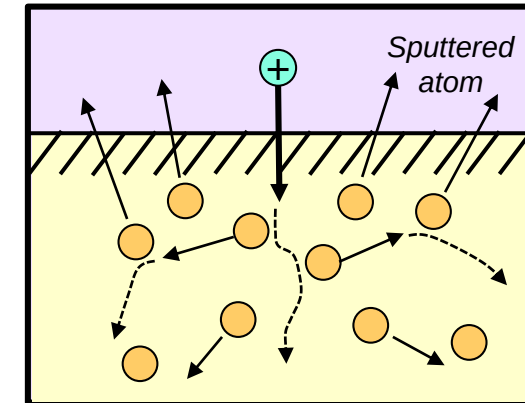
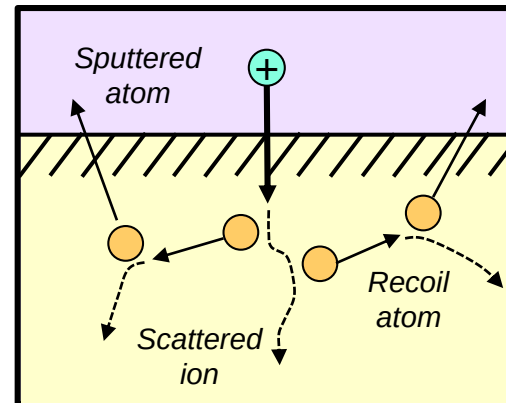
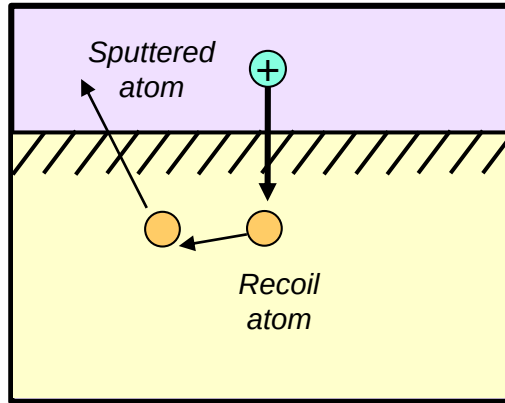


EP and Fusion PMI have complementary and overlapping considerations

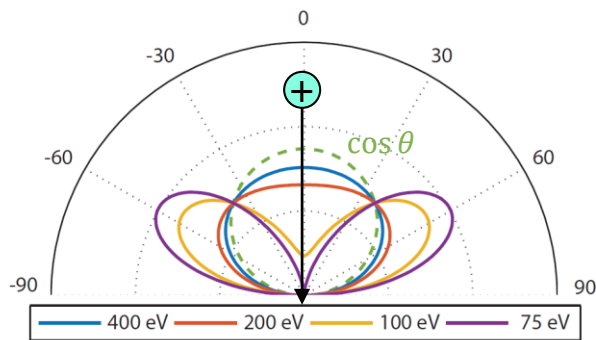
Plasma Sputtering Processes



Low Ion Energy Angular Sputtering Profile



Normal Incidence



Huerta, Matlock, Wirz (2016) JAP

Angular Sputtering Distribution

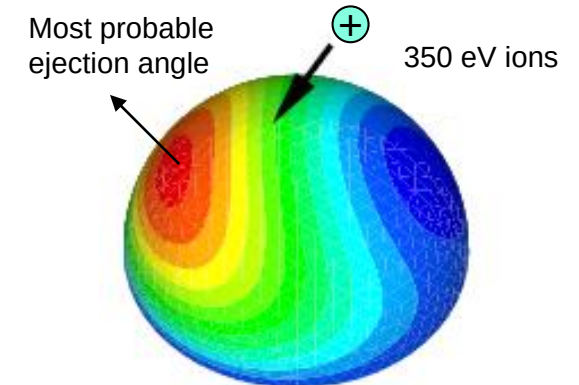
$$S(E, \theta, \alpha) \propto \cos \alpha \times \left[1 - \frac{1}{4} \sqrt{\frac{E_{th}}{E}} \left\{ \cos \theta \gamma(\alpha) + \frac{3}{2} \pi \sin \theta \sin \alpha \cos \phi \right\} \right]$$

$$\gamma(\alpha) = \frac{3 \sin^2 \alpha - 1}{\sin^2 \alpha} + \frac{\cos^2 \alpha (\sin^2 \alpha + 1)}{2 \sin^3 \alpha} \times \ln \left(\frac{1 + \sin \alpha}{1 - \sin \alpha} \right)$$

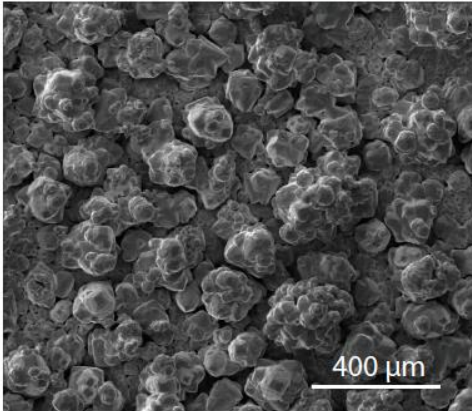
Normal incidence → “Butterfly” distribution at low energy
Oblique incidence → Forward-biased profile

Yamamura (1982) Rad Eff, Zhang and Zhang (2004) Raf Eff

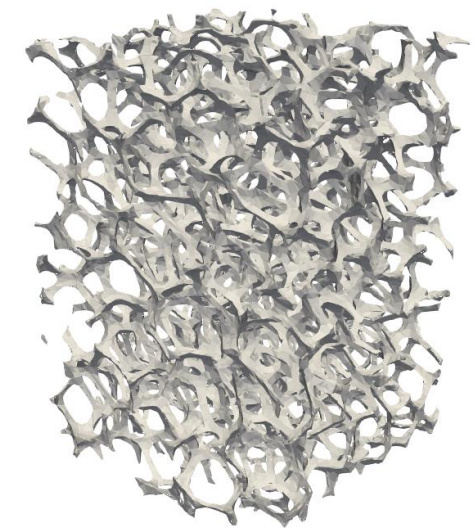
Oblique Incidence



Yalin, A. et al (2007)

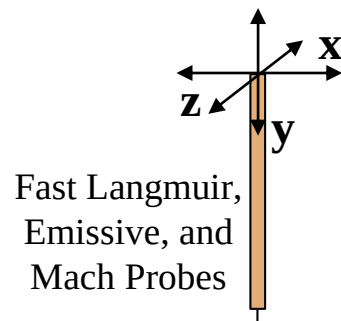
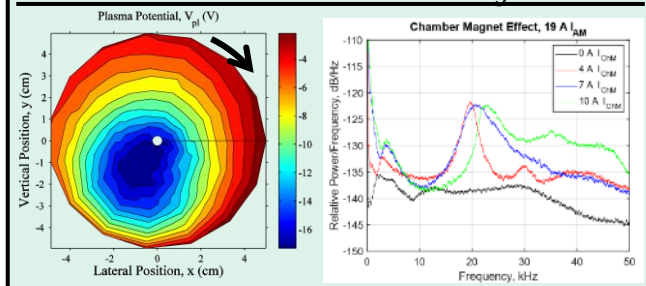


PMI FOR COMPLEX SURFACES AND MATERIALS

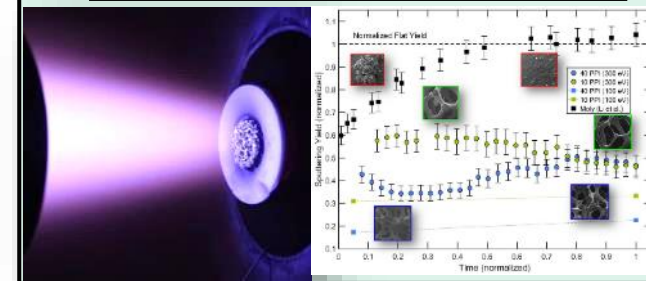


UCLA Pi Facility (top view)

Plasma Instabilities and Dynamics



Plasma-Material Interactions



Quartz Crystal Microbalance

θ

Sample Magnet

Target

High-speed Camera

Anode Gas Injection Ring

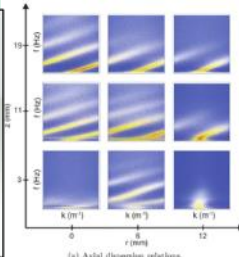
Anode

Chamber Magnets

Plasma Column

Cathode

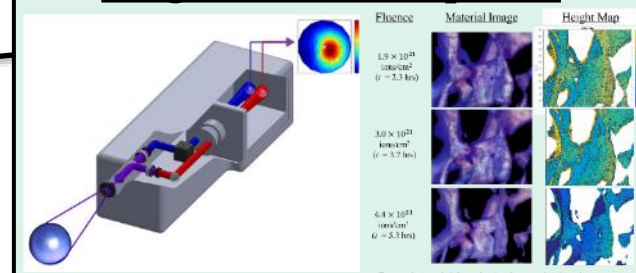
Hollow Cathode Physics



Spectroscopy Optics

Viewport

Diagnostics Development

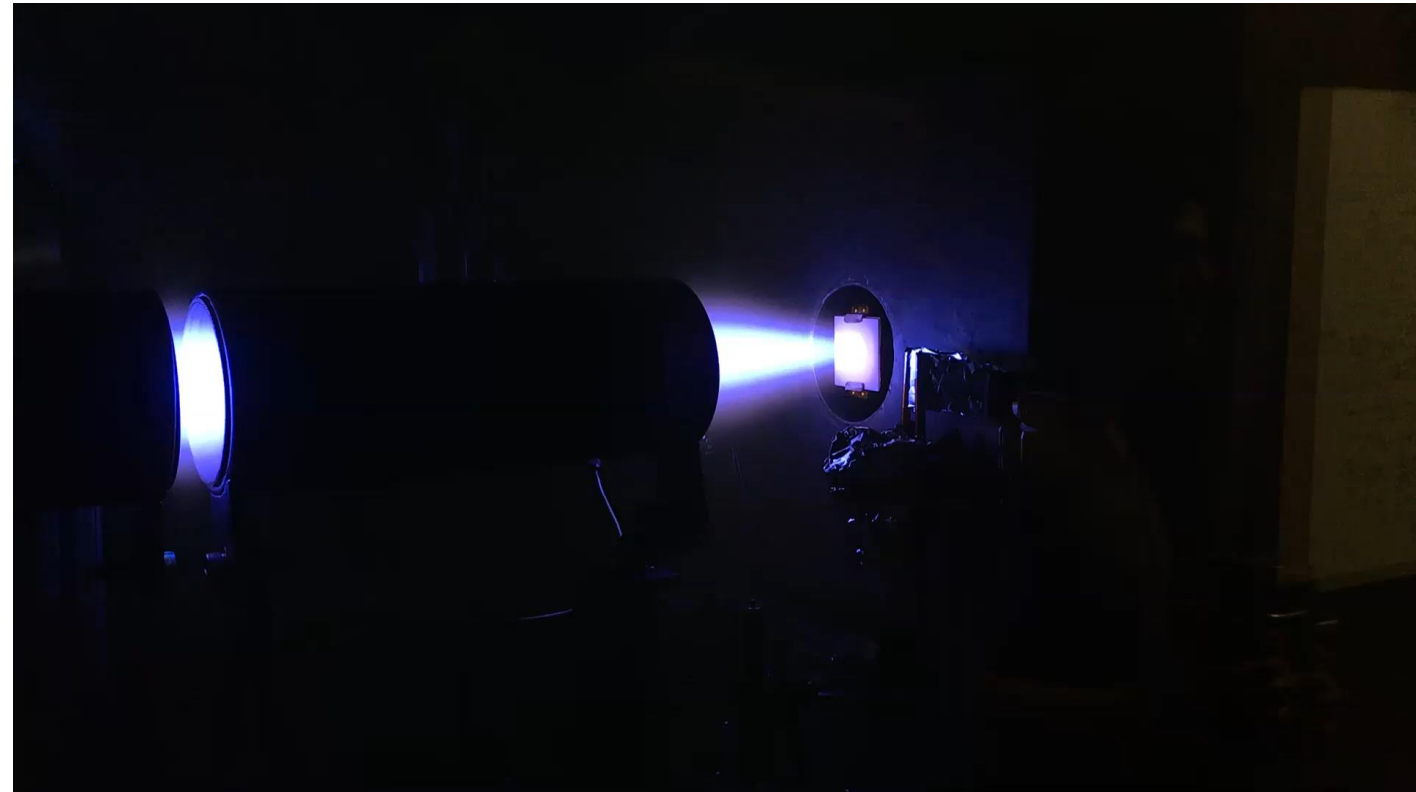
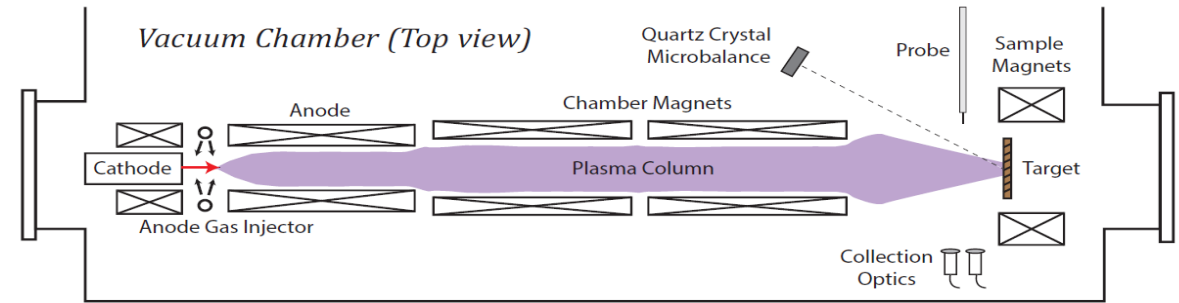


Plasma-interaction (Pi) Facility at UCLA

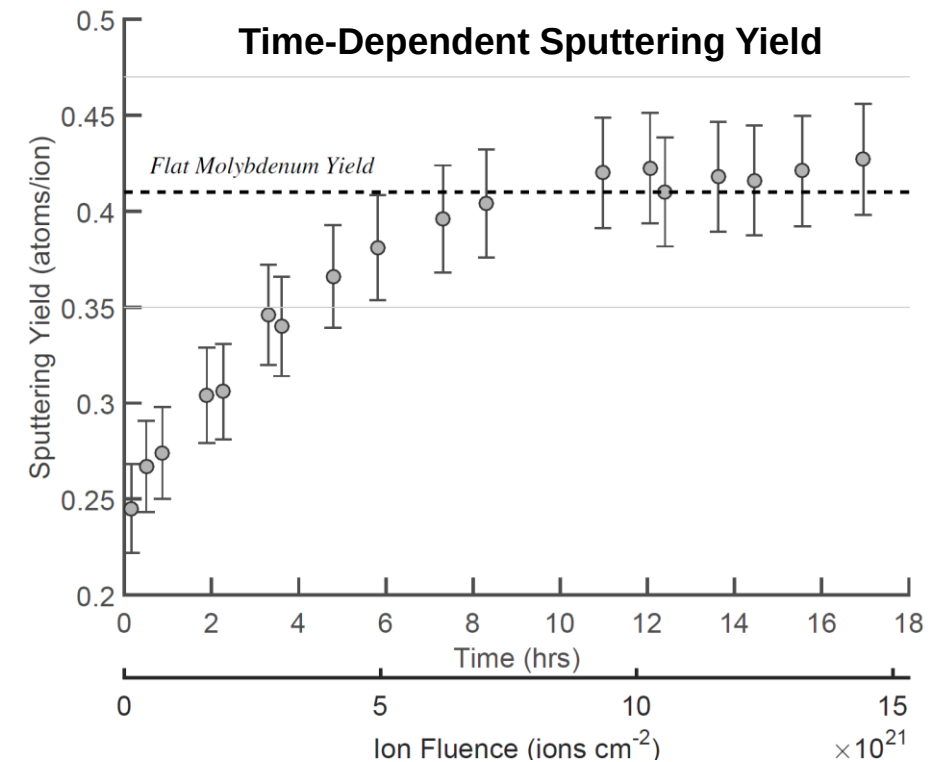
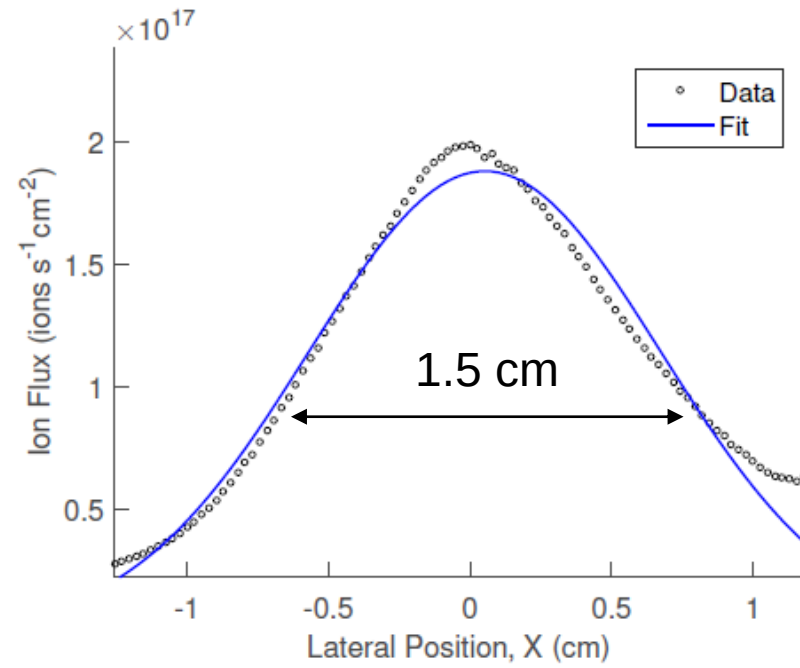
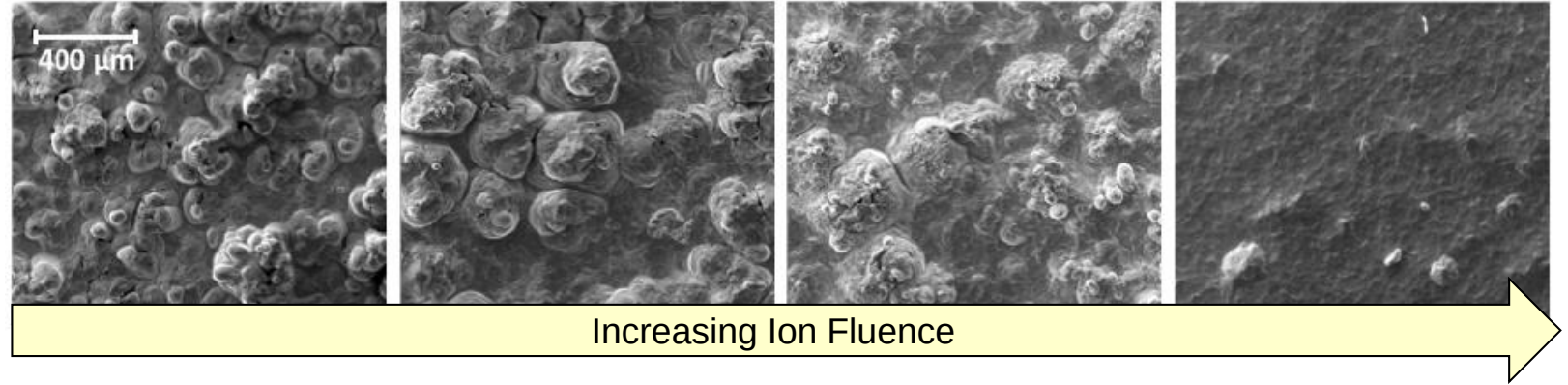
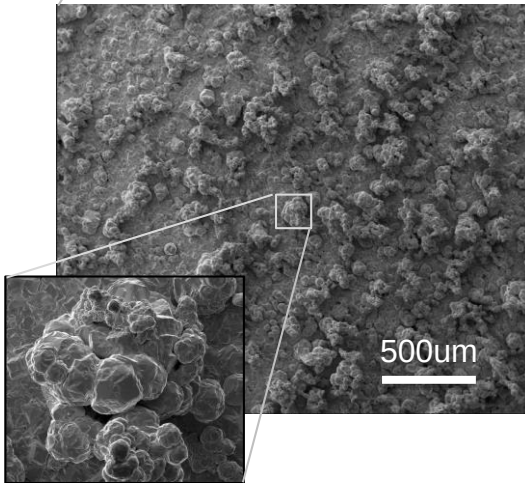
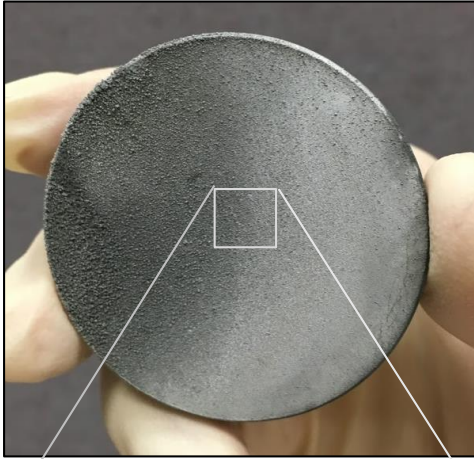
Pi is a magnetized, focused hollow cathode plasma onto material target

Type	Diagnostic	Measured Parameters
Non-intrusive	Quartz Crystal Microbalance (QCM)	Differential sputtering rate, sputtering yield
	Long Distance Microscope (LDM)	Surface visualization, height map
	Optical Emission Spectroscopy (OES)	n_e , T_e and n_n of sputterant species
	Laser Induced Fluorescence (LIF)	Ion/neutral velocity distribution function
	Laser Absorption Spectroscopy (LAS)	n_n , T_n of sputterant species
Semi-intrusive	Langmuir Probe	n_e , T_e
	Faraday Probe	1-sided ion flux
	Emissive Probe	Plasma potential
	Retarding Potential Analyzer	Ion energy distribution
Ex-situ	SEM/EDS/TEM/XPS/Laser Profilometry	Comprehensive surface mapping

Parameter	Range
Plasma density	10^{18} m^{-3}
Electron temperature	7 eV
Ion energy	40 to 400 eV
Ion flux to target*	$10^{17} \text{ cm}^{-2} \text{ s}^{-1}$
Target area	$\approx 1.8 \text{ cm}^2$

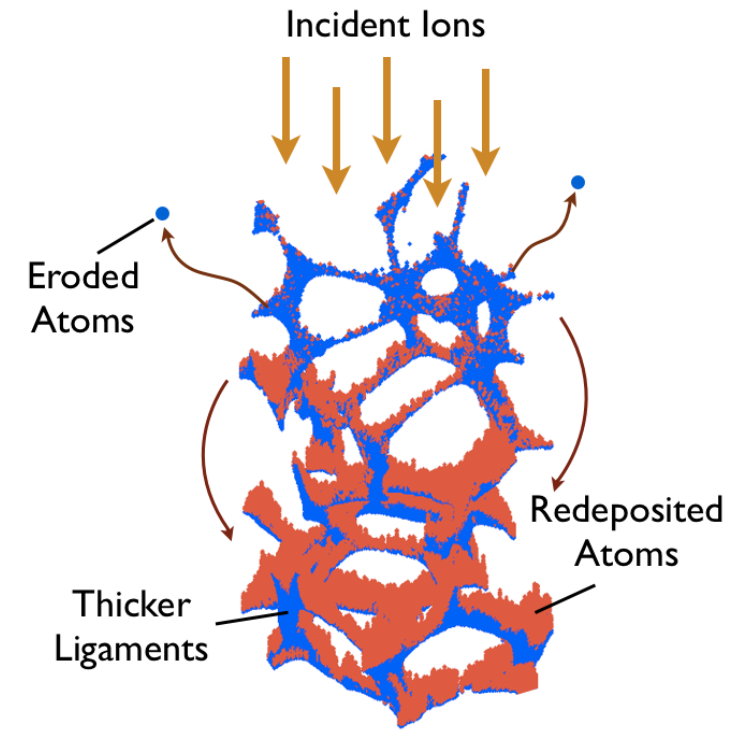
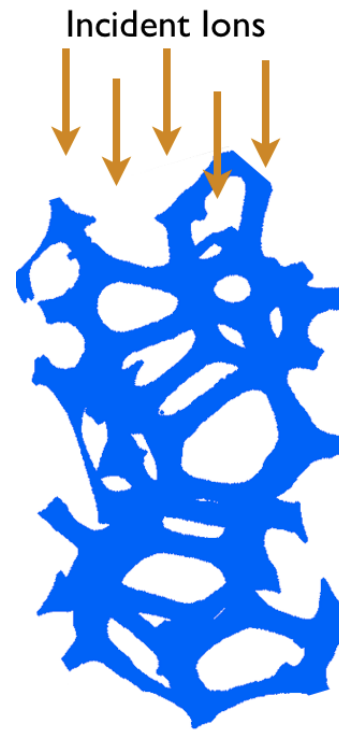
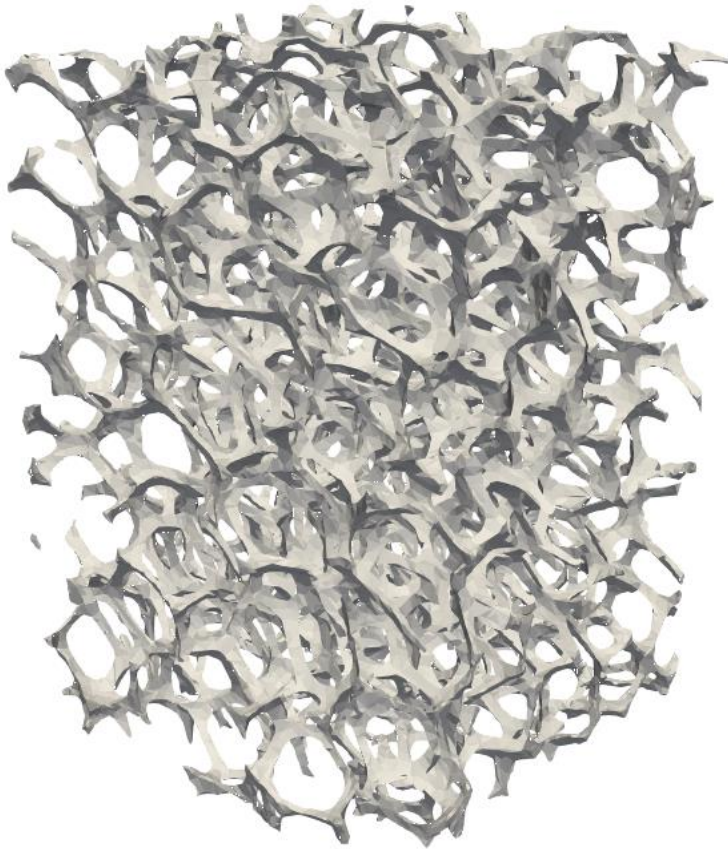


Sputtering Micro-structured Molybdenum



- [1] Li, G, Matlock, T, Goebel, D, Dodson, C, Wirz, R, Matthes, C, Ghoniem, N (2017) *Plasma Sources Sci. Tech.*
 [2] Matthes, C, Ghoniem, N, Li, G, Matlock, T, Goebel, D, Dodson, C, Wirz, R (2017) *Appl. Surf. Sci.*

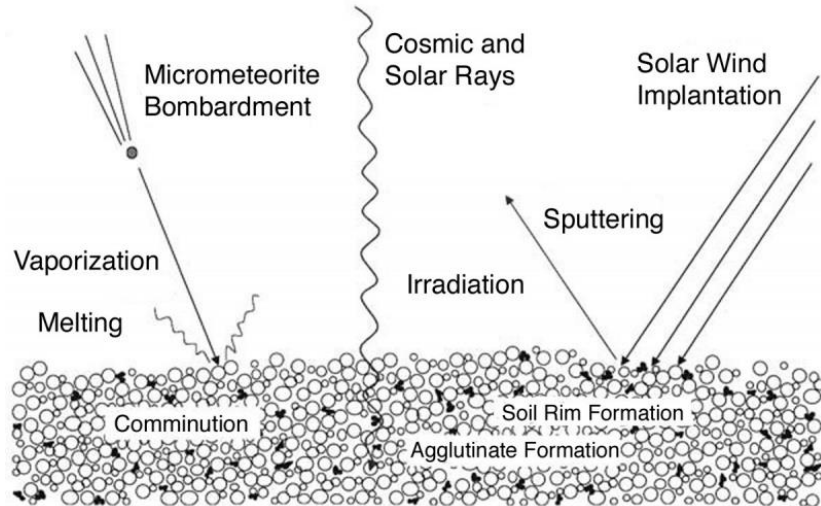
Plasma-Resilient Foams?



Ghoniem, Marian, Po, Wirz,
"Resilient Self-Healing Materials for the Extreme Environment of Space Electric Propulsion & Power," AFOSR Aug 2016

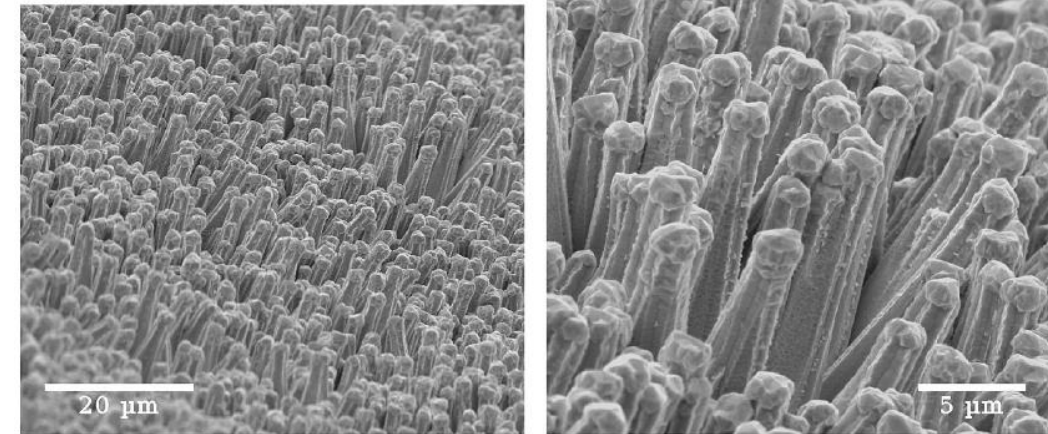
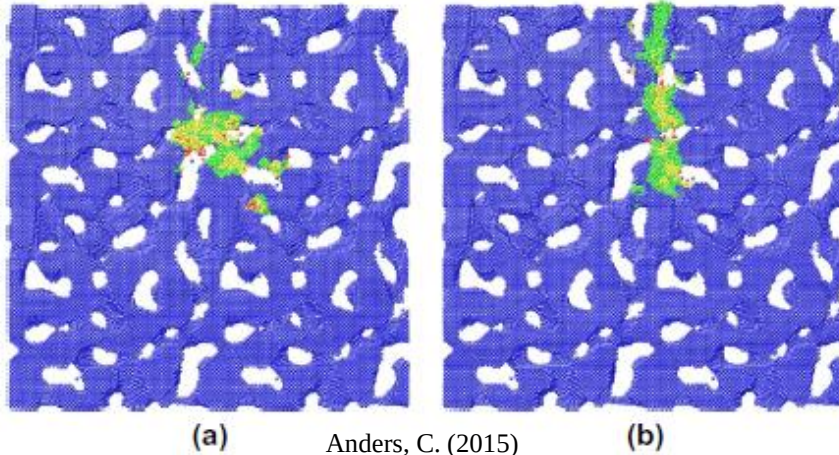
Past Research on Foam-like Sputtering

Lunar Regolith as “nanofoam”



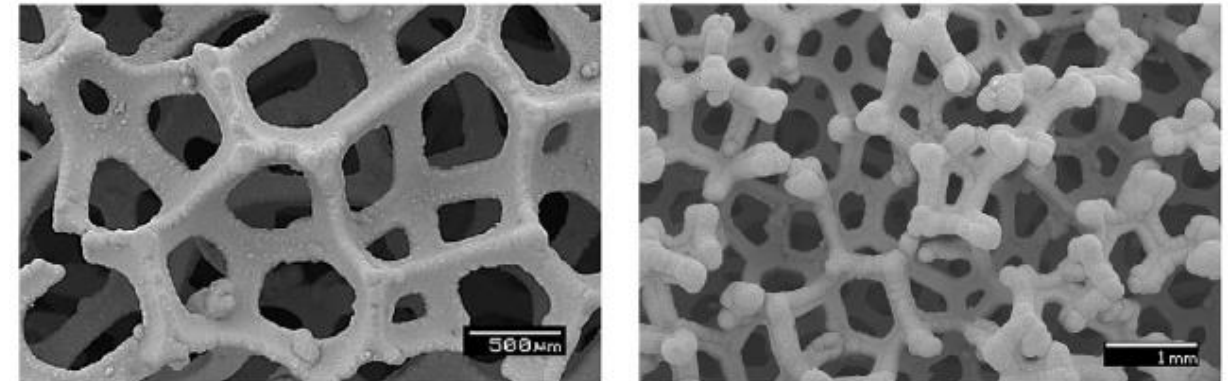
Hapke, B. and Cassidy, W., “Is the moon really as smooth as a billiard ball? Remarks concerning recent models of sputter-fractionation on the lunar surface,” *Geophysical Research Letters*, Vol. 5, No. 4, 1978.

10 keV sputtering of nanofoams



Thermal stress reduction and greater ductility of W-coated Re pillars

Rivera D., Wirz R.E., Ghoniem N.M., “Experimental measurements of surface damage and residual stresses in micro-engineered plasma facing materials,” *Journal of Nuclear Materials* 486, pp. 111-121 (April 2017)



80 – 200 eV Helium Sputtering of Tungsten Foam

Gao, E. et al (2018, 2019)

Long Distance Microscopy and ex-situ diagnostics

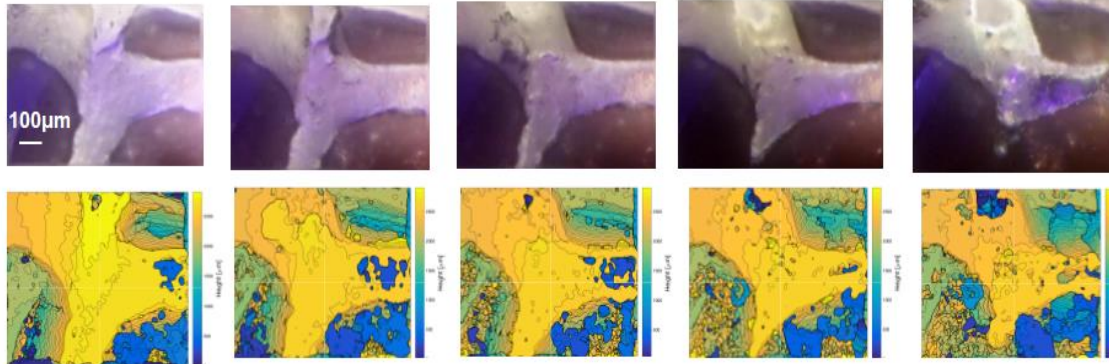
In-situ foam erosion visualization

In-situ Long Distance Microscopy for real-time surface evolution video of a foam surface during sputtering erosion

- First-ever in-situ observation of plasma interaction with a textured surface (2016)
- Ottaviano A., Thuppul A., Hayes J., Dodson C., Li G., Chen Z., and Wirz, R.E., "In-situ Microscopy of Ion-Induced Sputter Erosion of a Featured Surface," submitted, Rev. Sci. Inst., 2021



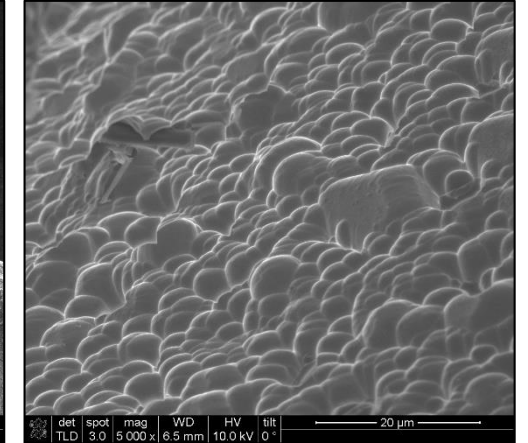
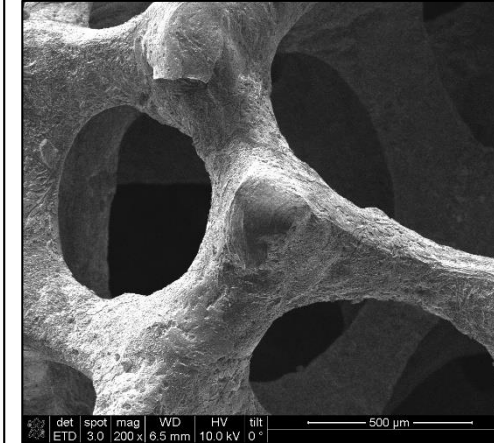
Images



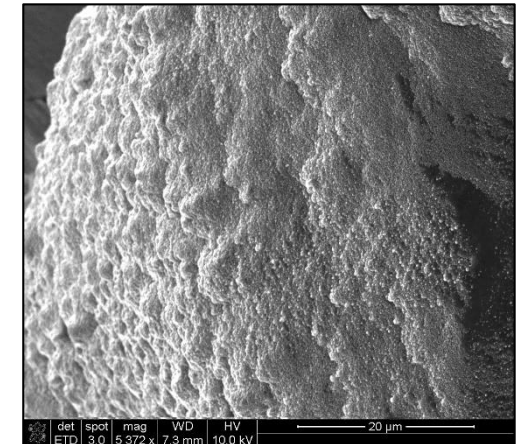
Focus Variation Profilometry

Exposure time: 0 hours	6 hours	12 hours	18 hours	24 hours
Fluence: 0 ions/cm ²	2.16×10^{21} ions/cm ²	4.32×10^{21} ions/cm ²	6.48×10^{21} ions/cm ²	8.64×10^{21} ions/cm ²

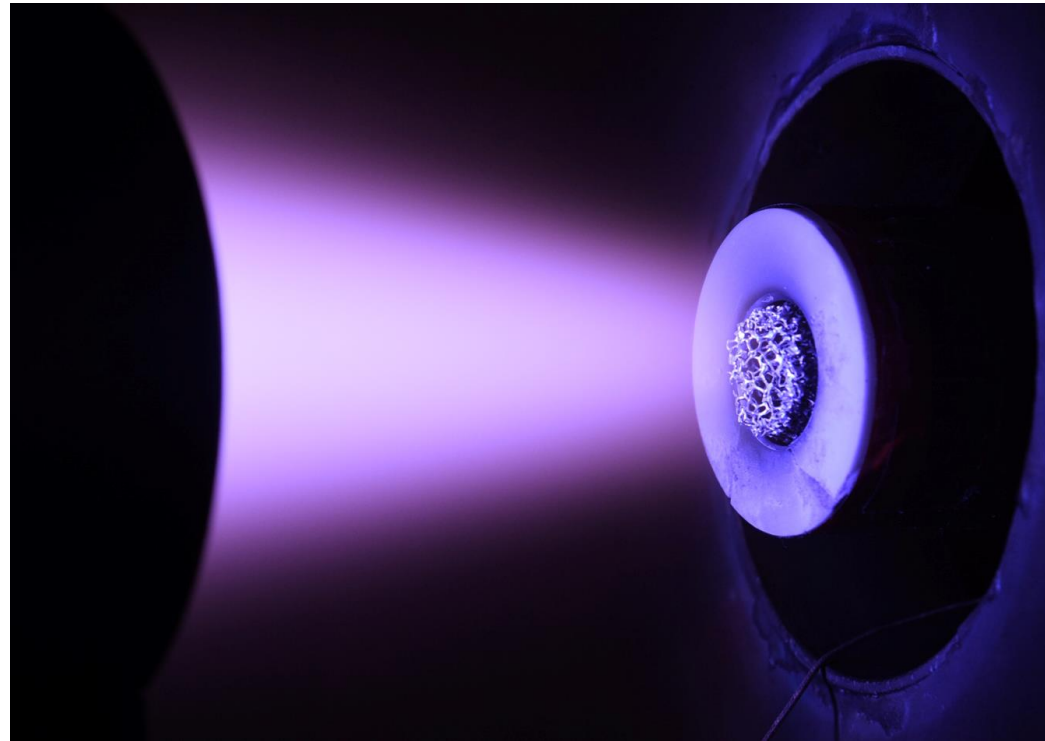
Pre-plasma exposure



Post-plasma exposure



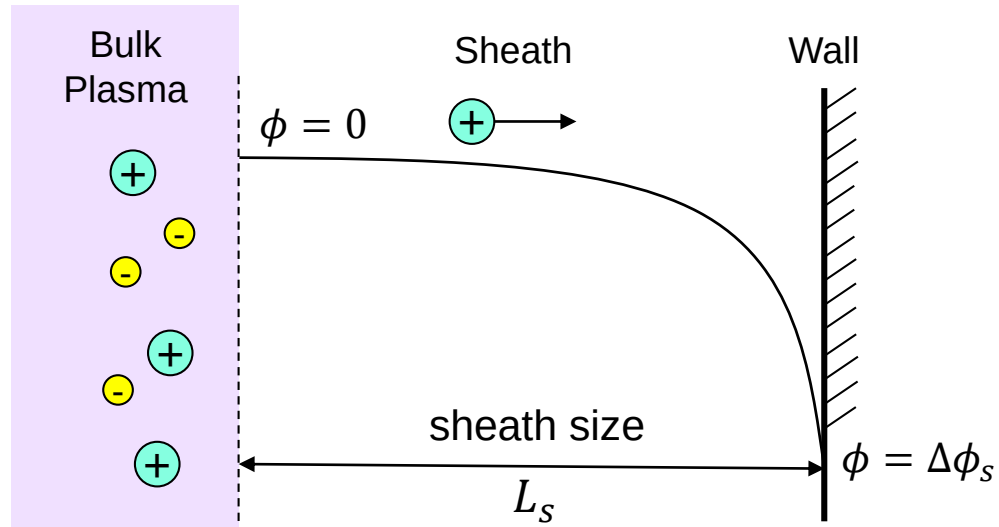
PERSISTENT SPUTTERING REDUCTION & PLASMA-INFUSED MATERIALS



Li G., Wirz R.E., "Persistent Sputtering Yield Reduction in Plasma-Infused Foams," *Physical Review Letters*, 126 (3), 035001 (2021)
<https://doi.org/10.1103/PhysRevLett.126.035001>

Plasma Sheaths and Foams

1D Ion Sheath ($\Delta\phi_s \gg T_e$)



Ions accelerated through sheath $E_{ion} = \Delta\phi_s$

Child-Langmuir Sheath

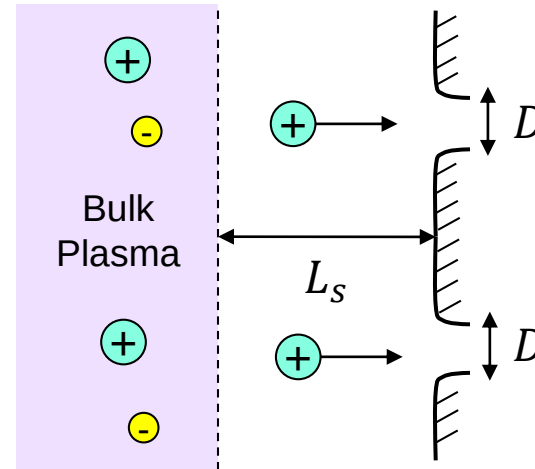
$$\frac{L_s}{\lambda_D} = \frac{\sqrt{2}}{3} \left(\frac{2e\Delta\phi_s}{T_e} \right)^{3/4}$$

Debye Length

$$\lambda_D^2 = \frac{\epsilon_0 k_B T_e}{n_e e^2}$$

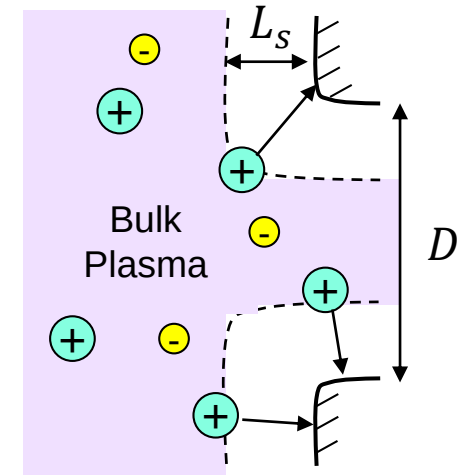
2D Ion Sheath and Foam Surface

Small Pores $D \ll L_s$



Sheath forms outside foam.

Large Pores $D \gg L_s$



Sheath conforms to surface.

Plasma Infusion Parameter, $\xi = \frac{D}{L_s}$

$$\xi = \frac{D}{L_s} \propto \frac{D \sqrt{n_e} T_e^{1/4}}{\Delta\phi^{3/4}}$$

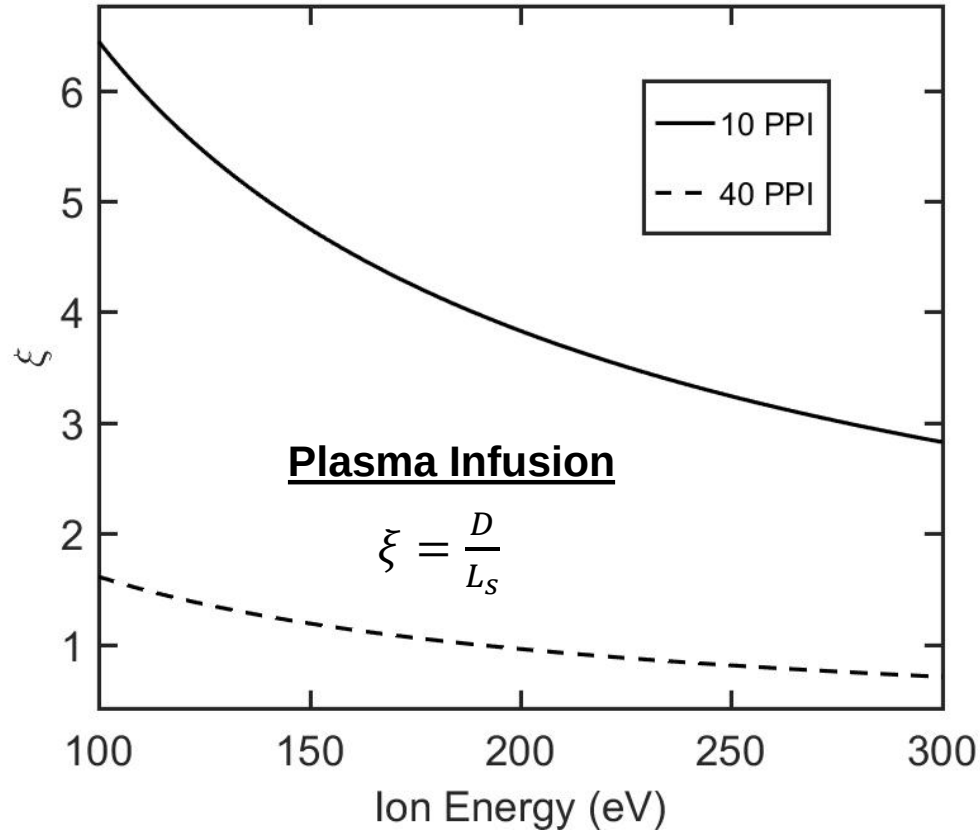
$\xi \ll 1 \rightarrow$ Plasma-Facing

$\xi \gg 1 \rightarrow$ Plasma-Infused

$\xi \approx 1 \rightarrow$ Transition Region

[1] Baalrud, S. et al (2020) Plasma Sources Sci. Tech.

Aluminum Foam Experiments



40 PPI

$$\xi_{40} \approx 0.7 - 1.7$$

Transitional
Regime



10 PPI

$$\xi_{10} = 2.8 - 6.5$$

Partially
Plasma-infused



Test Conditions

- 100 - 300 eV argon ions
- 2×10^{-6} Torr (base)
- 30 hrs total duration over 3 days

*PPI = Pores Per Inch

Sheath size in Pi

$$\lambda_D = \sqrt{\frac{\epsilon_0 k_B T_e}{n_e e^2}} \sim 50 \mu\text{m}$$

$n_e \sim 10^{17}$
 $T_e \sim 5 \text{ eV}$
 $\Delta\phi_s \sim 300 \text{ V}$

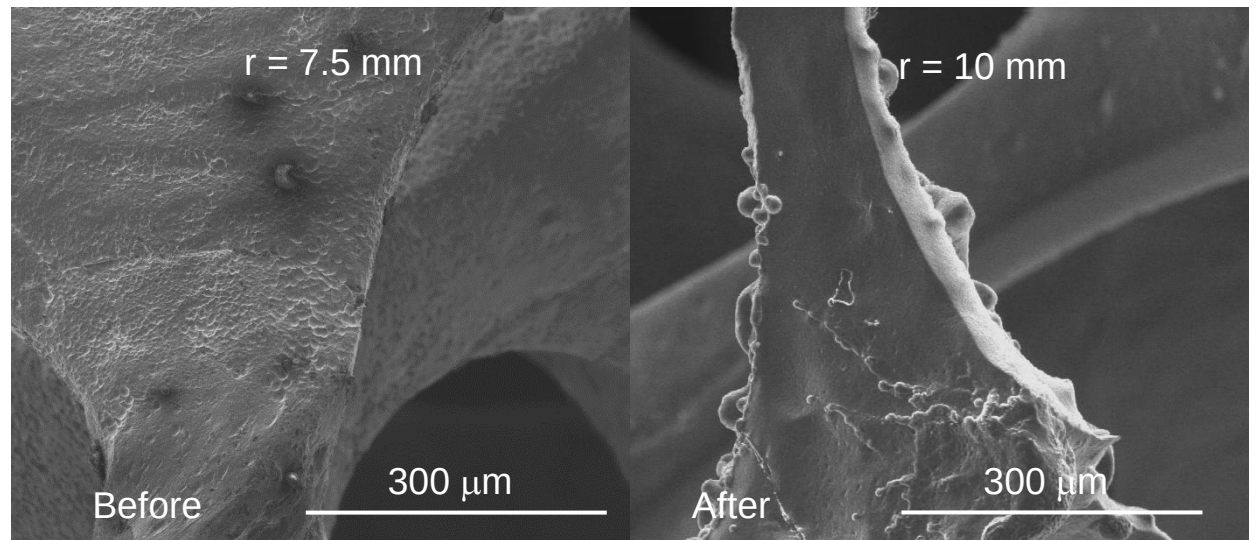
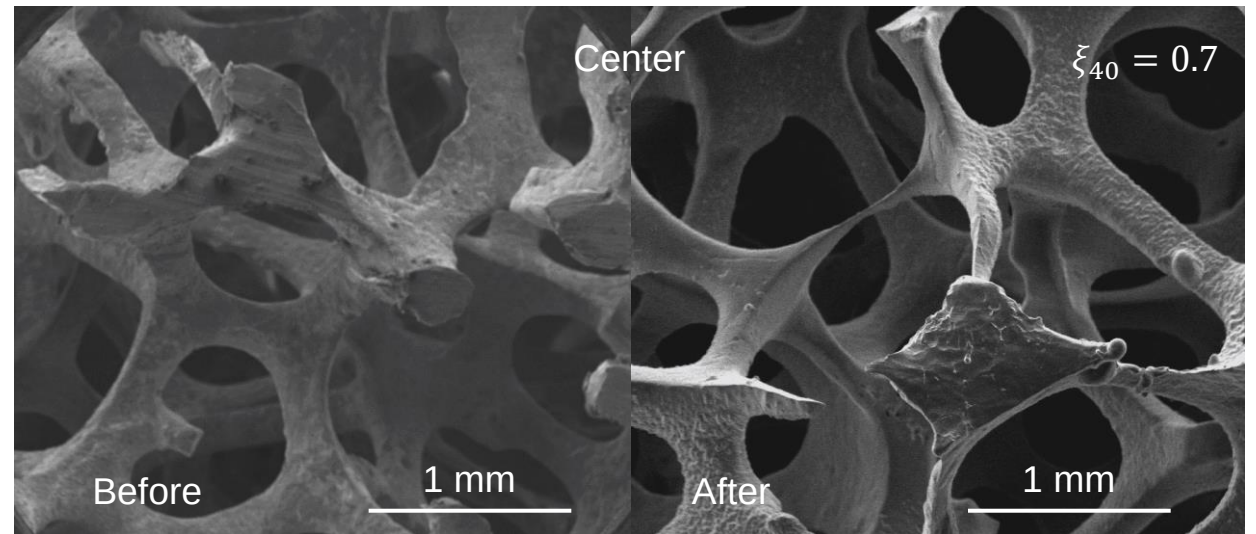
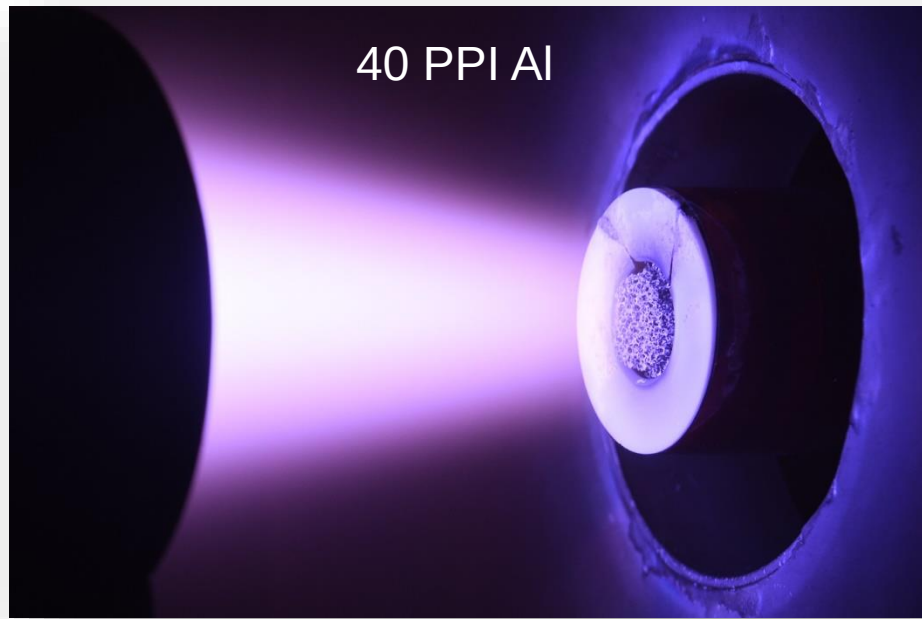
$$L_s = \frac{\sqrt{2}}{3} \left(\frac{2e\Delta\phi_s}{T_e} \right)^{3/4} \lambda_D = 850 \mu\text{m}$$

Foam Geometry

$$10 \text{ PPI} \rightarrow D = 1.52 \text{ mm}$$

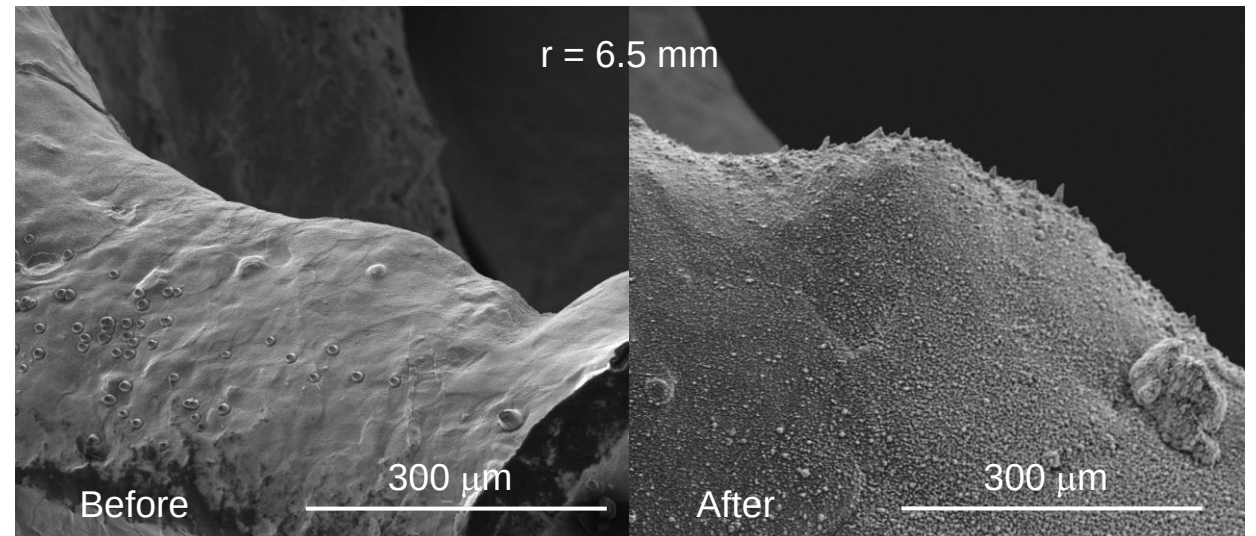
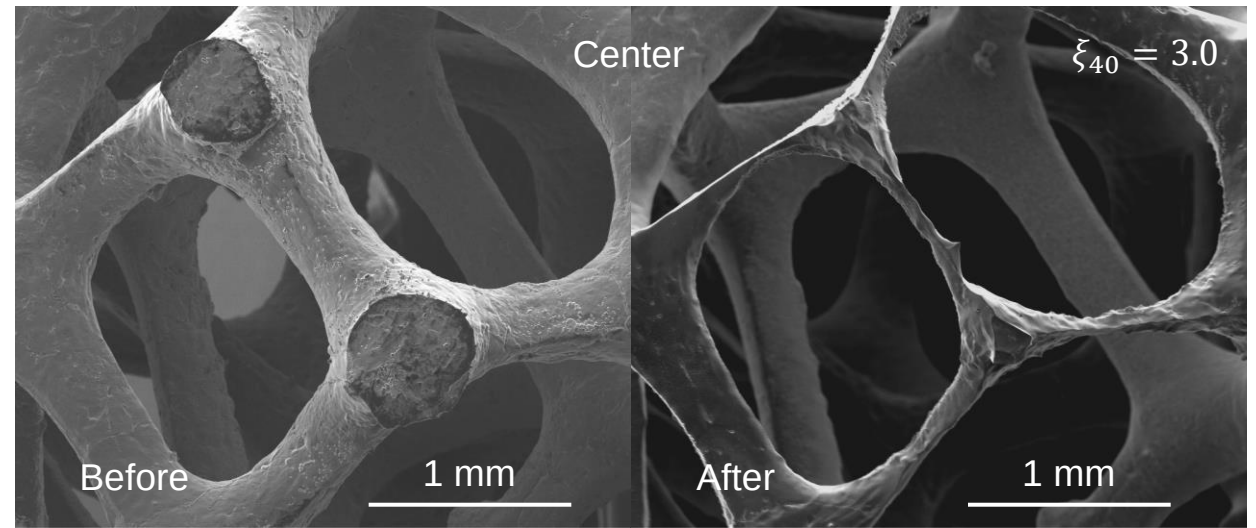
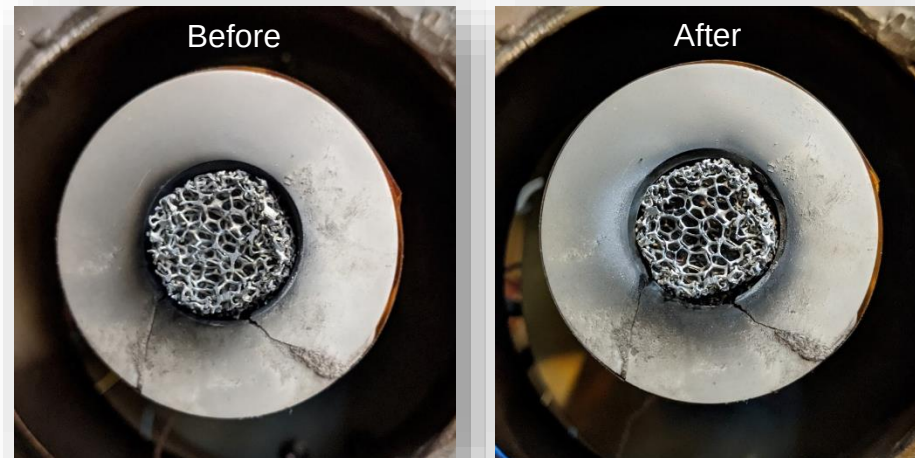
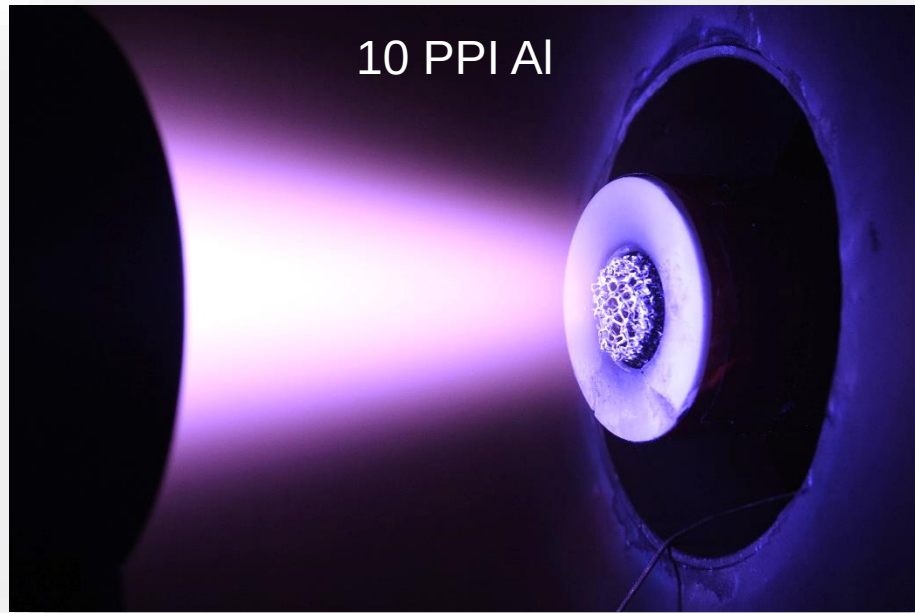
$$40 \text{ PPI} \rightarrow D = 381 \mu\text{m}$$

Test Observations – 40 PPI Al foam

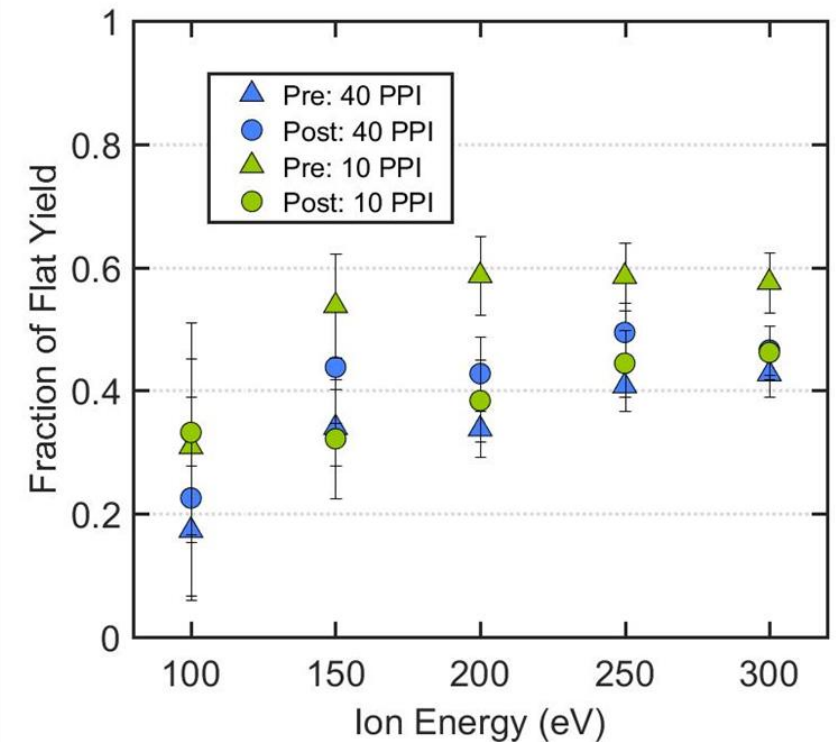
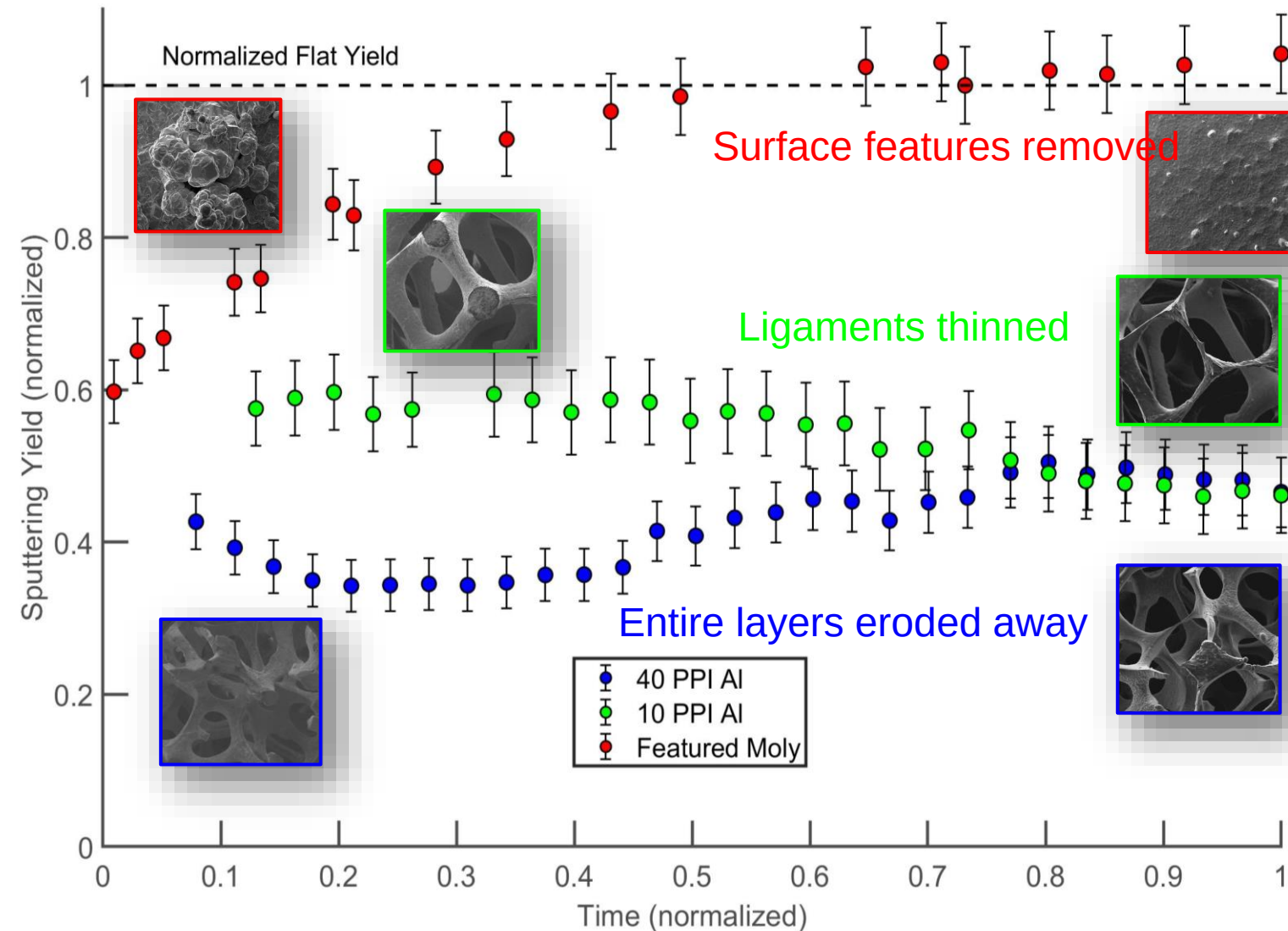


Note: different features

Test Observations – 10 PPI Al foam

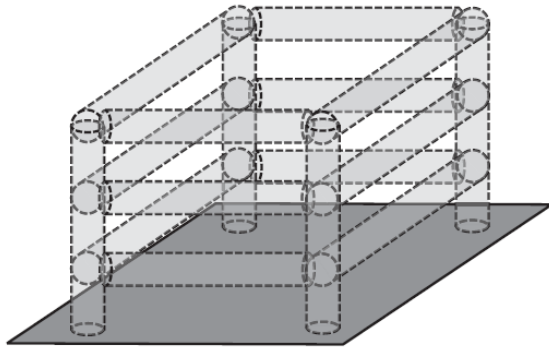


Sputtering Yield of Volumetrically Architected Materials

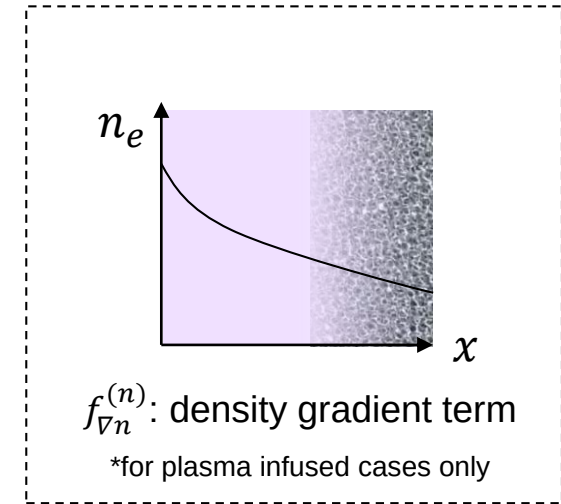
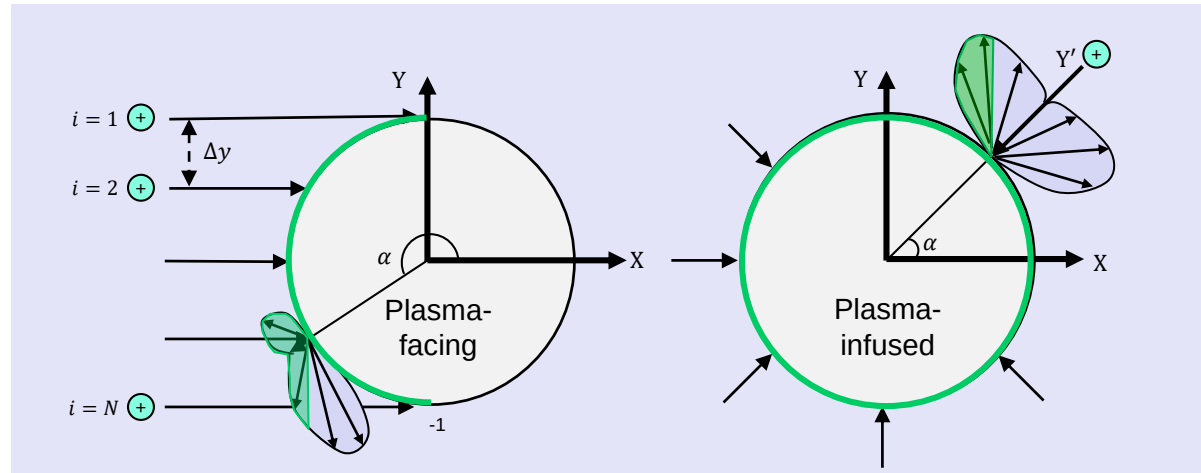


Analysis of Plasma-foam Sputtering Behavior

3D cage geometry

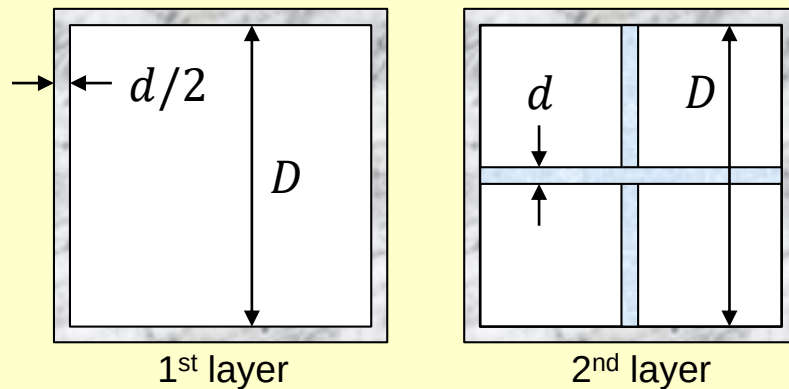


Huerta, Patino, Wirz (2018) J. Phys. D

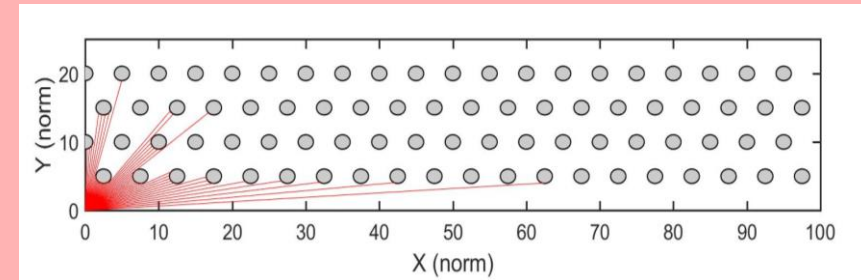


$$Y_{eff} = Y_{flat} \sum_{n=1}^N (1 - p^{(n)}) f_A f_\beta \left(1 - f_{dep}^{(n)} \right) f_{\nabla n}^{(n)}$$

Opacity

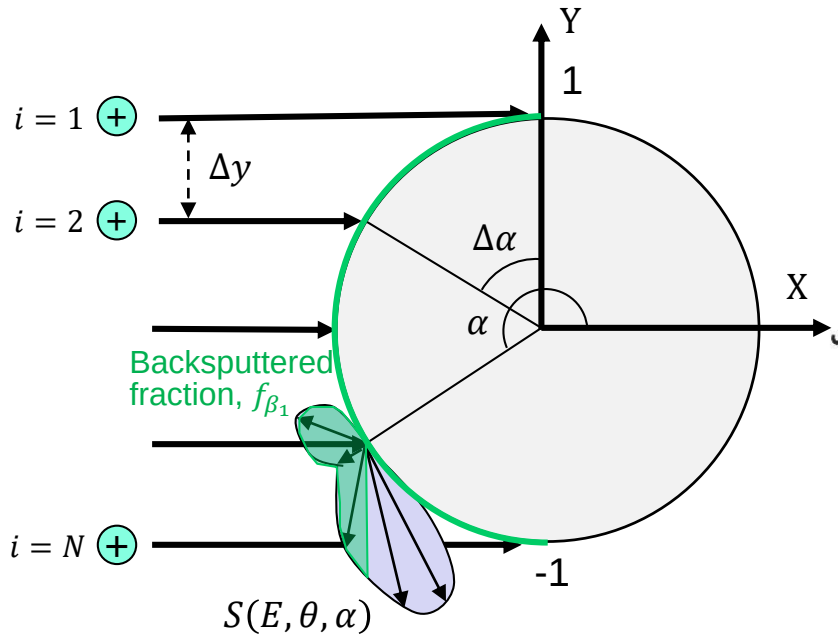


Ballistic Deposition



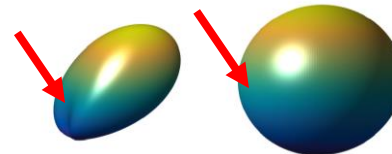
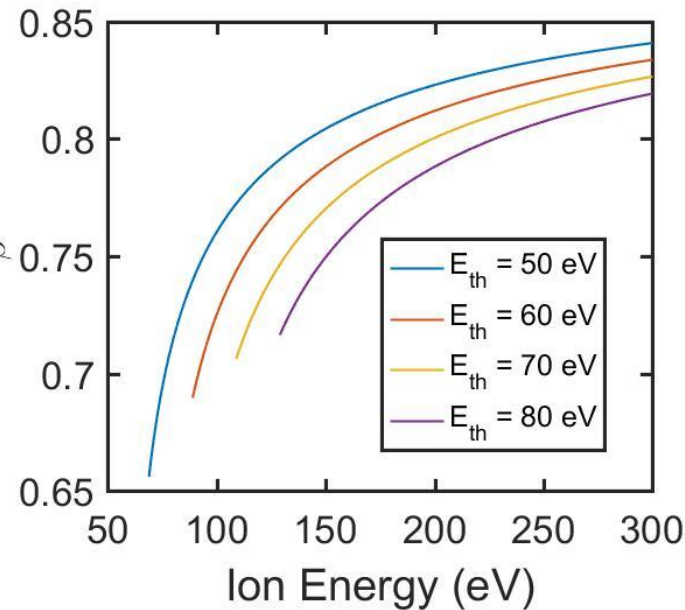
Area Factor, f_A , and Backsputter Fraction, f_β

Plasma-facing



Low Energy Angular Sputtering Profile

$$S(E, \theta, \alpha) \propto \cos \alpha \times \left[1 - \frac{1}{4} \sqrt{\frac{E_{th}}{E}} \left\{ \cos \theta \gamma(\alpha) + \right. \right.$$



$$f_\beta = \frac{1}{N} \sum f_{\beta_i} \sim 0.8$$

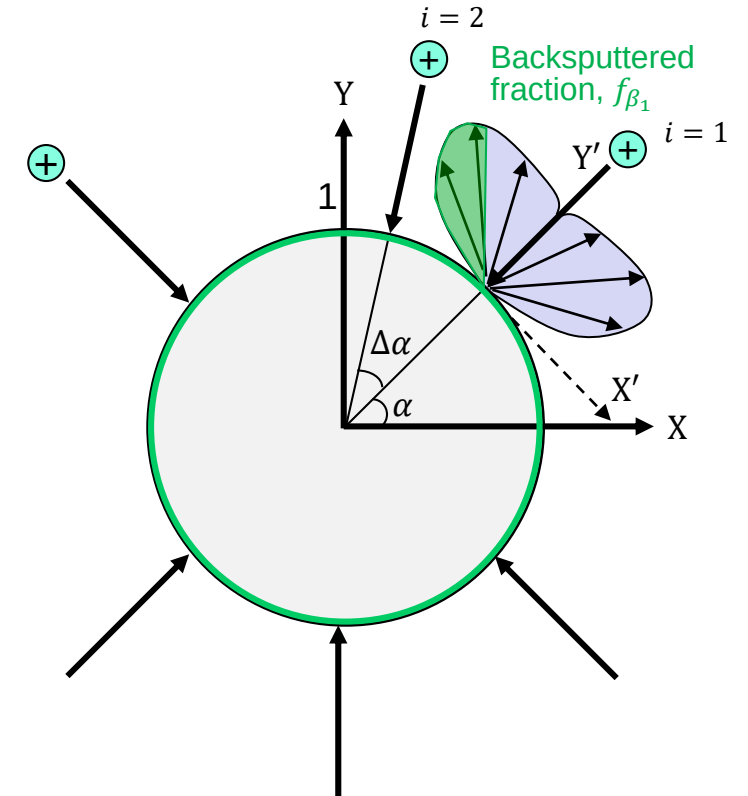
Numerically iterate through ion impacts.

Dependent on ion energy

$$f_A = \frac{dD}{dD} = 1$$

Sensitive to sputtering threshold energy.

Plasma-infused

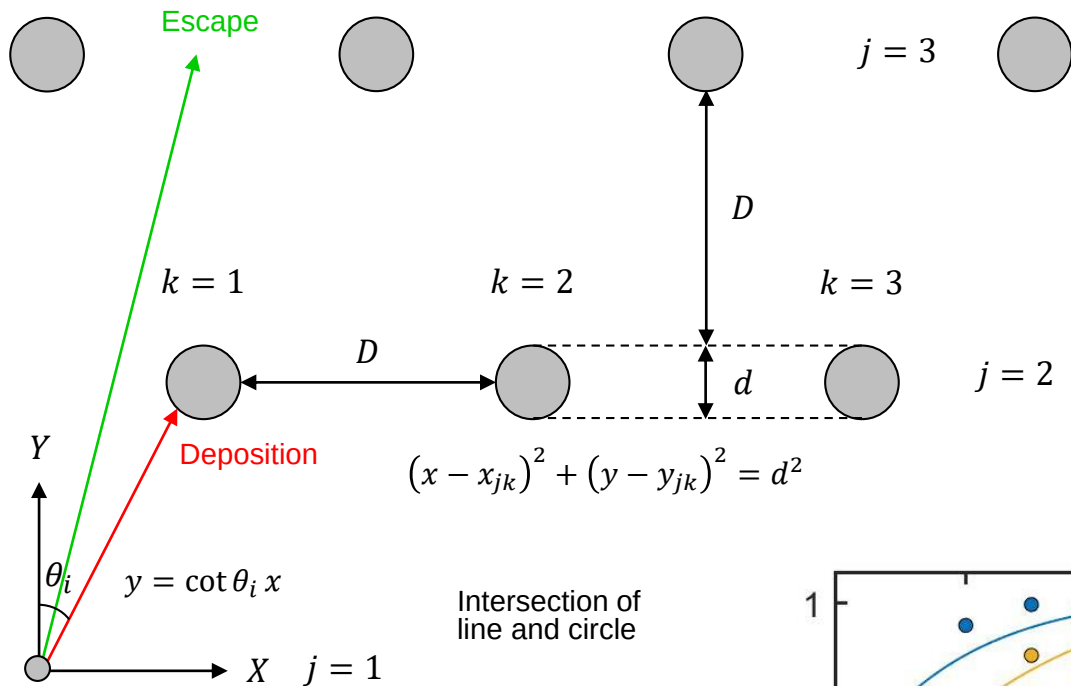


$$f_\beta = \frac{1}{N} \sum f_{\beta_i} = 0.5$$

Symmetry

$$f_A = \frac{2\pi(d/2)D}{dD} = \pi$$

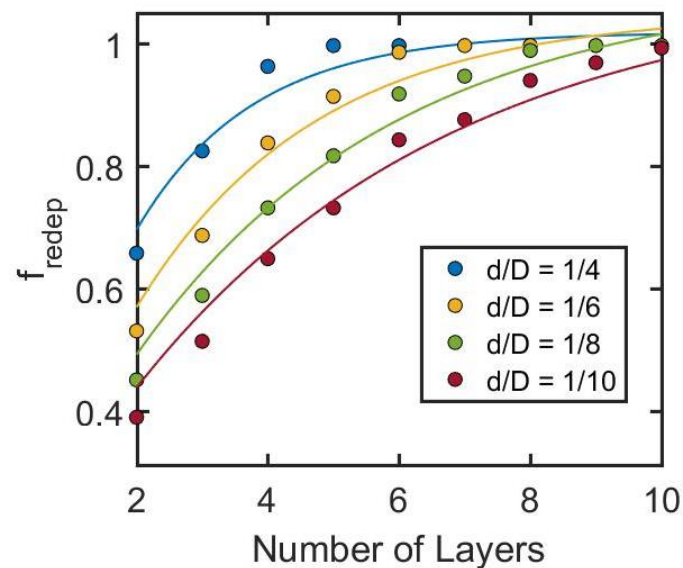
Ballistic Deposition Factor, f_{dep}



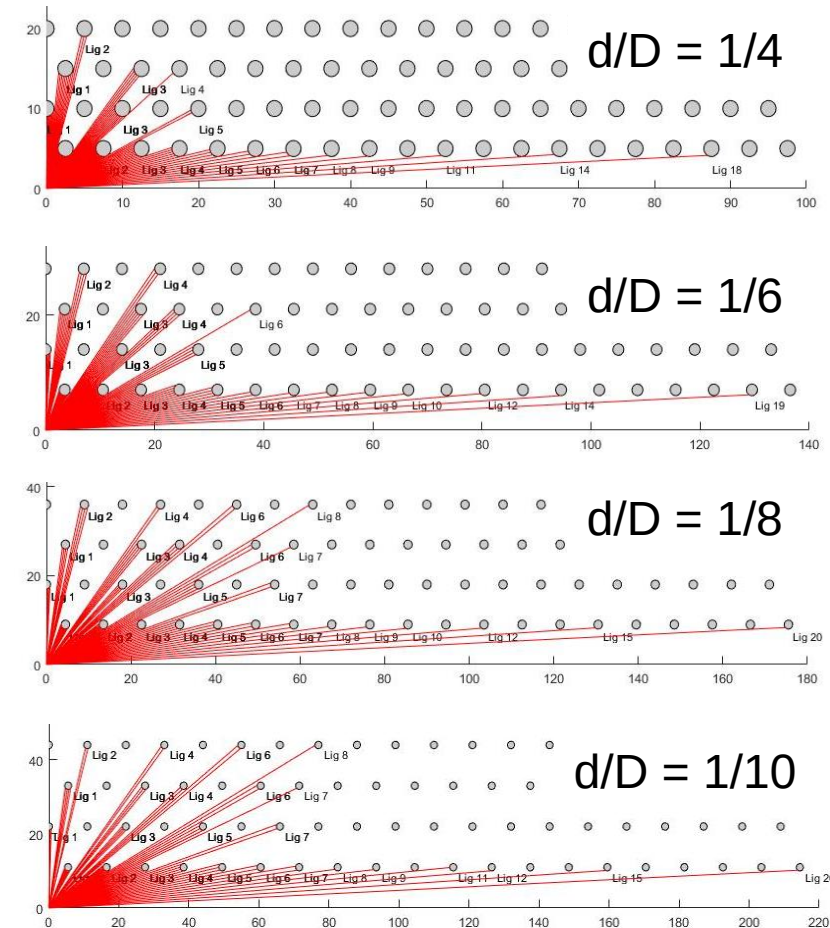
Point source sputterant emission

$$f_{\text{dep}} = f_0 + \left[1 - \exp\left(-\frac{N}{N'}\right) \right]$$

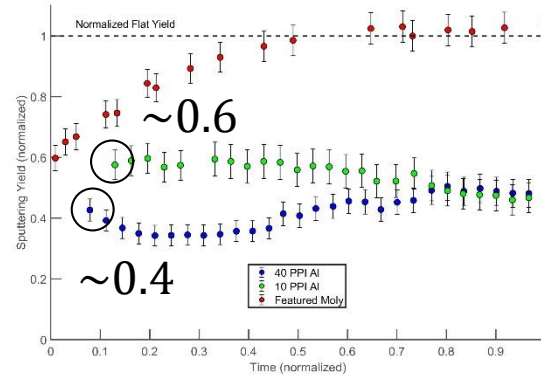
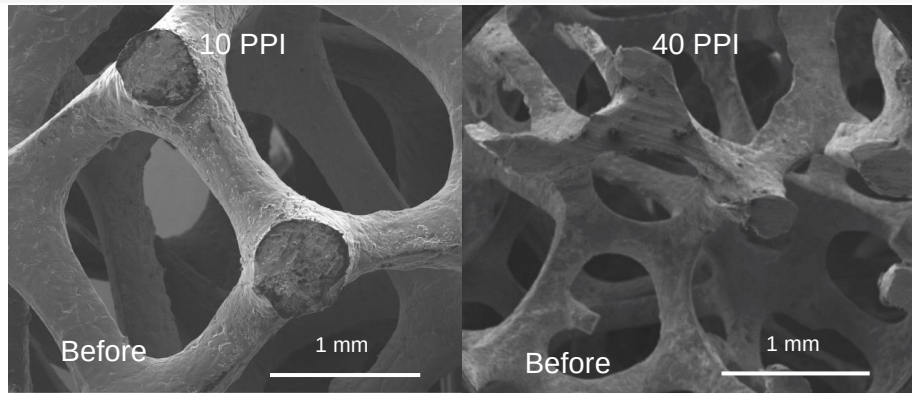
Analogous to particle mean free path scenario.



Example of Varying Ratios

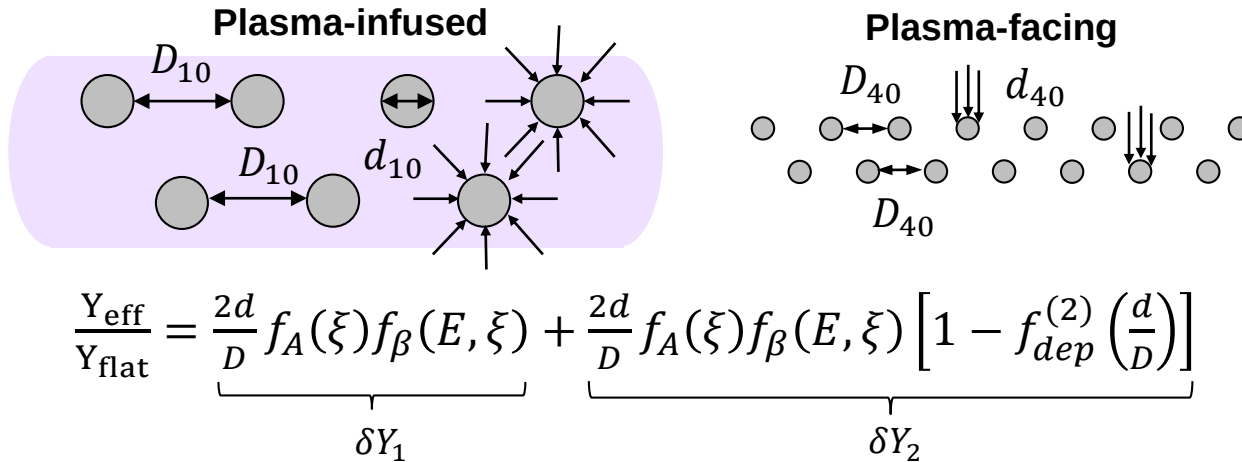


Case Study 1: 10 PPI Yield greater than 40 PPI Yield



Observations:

- 10 PPI foam initially has a larger yield with 300 eV Ar⁺ than 40 PPI foam
- 10 PPI has smaller pore density but thicker ligaments compared to 40 PPI
- $\xi_{10} = 3.0 > \xi_{40} = 0.7$ ($\xi = \frac{D}{L_s}$)



Case	δY_1	δY_2	$Y_{\text{eff}}/Y_{\text{flat}}$
Plasma-infused	0.52	0.25	0.77
Plasma-facing	0.28	0.13	0.41

$$\frac{d_{10}}{D_{10}} \approx \frac{d_{40}}{D_{40}} \approx \frac{1}{6}$$

Same self-similar dimensions.

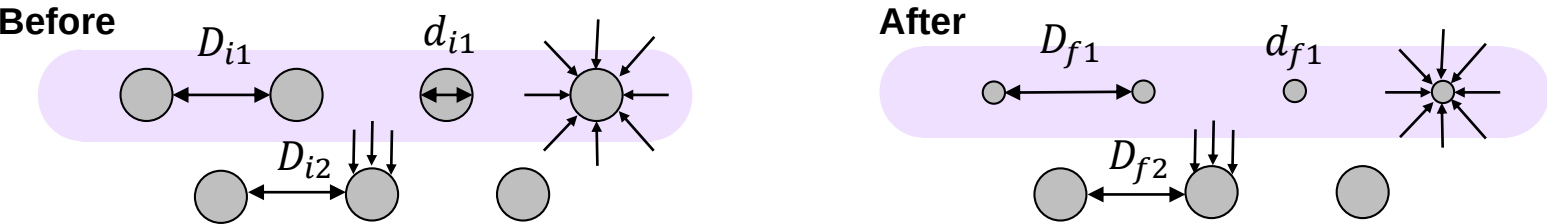
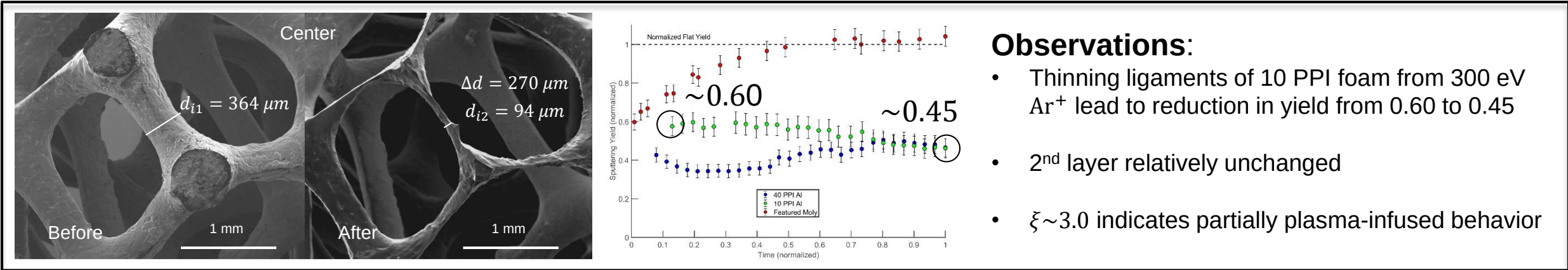
$$\frac{\text{Plasma-infused } f_A(10 \text{ PPI}) f_\beta(10 \text{ PPI})}{\text{Plasma-facing } f_A(10 \text{ PPI}) f_\beta(40 \text{ PPI})} \approx 2$$

Plasma-infused has larger effective sputtering area.

Conclusion:

- 10 PPI sample initially has a larger yield due to higher effective sputtering area from more plasma-infusion compared to 40 PPI foam

Case Study 2: Thinning Ligaments (10 PPI)



1st Layer - Plasma-infused (PI)

2nd Layer - Plasma-facing (PF)

$$\frac{Y_{\text{eff}}}{Y_{\text{flat}}} = \underbrace{\frac{2d_1}{D_1} f_{A1}(\xi) f_{\beta 1}(E, \xi)}_{\delta Y_1} + \underbrace{\frac{2d_2}{D_2} f_{A2}(\xi) f_{\beta 2}(E, \xi)}_{\delta Y_2} \left[1 - f_{\text{dep}}^{(2)}\left(\frac{d_1}{D_1}\right) \right]$$

Case	δY_1 (PI ₁)	δY_2 (PF ₂)	$Y_{\text{eff}}/Y_{\text{flat}}$ (PI ₁ ,PF ₂)	$Y_{\text{eff}}/Y_{\text{flat}}$ (PI ₁ ,PI ₂)	$Y_{\text{eff}}/Y_{\text{flat}}$ (PF ₁ ,PF ₂)
Before	0.45	0.12	0.57	0.77	0.36
After	0.10	0.20	0.30	0.47	0.25

Conclusions:

I. Yield for thinning ligaments decreases due to larger effect of lower opacity of 1st layer than reduced deposition

II. 10 PPI foam is in a partially-infused regime

Conclusions and Path Forward

Conclusions

- Persistent sputtering yield is possible with volumetrically complex surfaces
- Plasma-infused materials offer a unique plasma-material boundary

Path Forward

- Many explorations, including...
- Increased plasma and thermal loading
- Analysis of material property evolution
- Geometry and material optimization with fusion-relevant materials
- Opportunities for electron conduction and thermal energy transport for high-energy plasma applications
- Applications include propulsion, fusion, hypersonics, manufacturing, etc.

DOE/ARPA-E/FES GAMOW Project:

AMPERE: Advanced Materials for Plasma-Exposed Robust Electrodes

